

# Wavefront preserving optics development for high power FELs



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Physics & Applications  
of High Efficiency  
Free-Electron Lasers Workshop  
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California NanoSystem Institute*



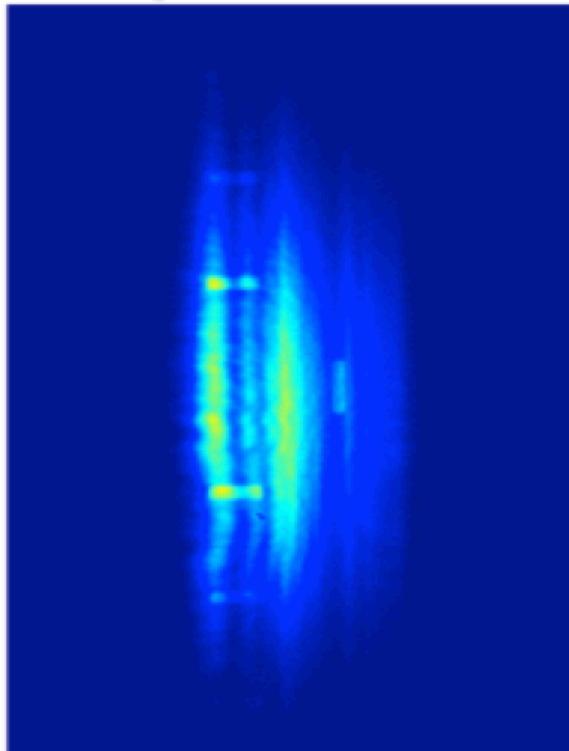
# Wavefront preserving optics development for high power FELs

**subtitle: how to go from**

**this**

**to this**

**...and preserve it with an high power source**



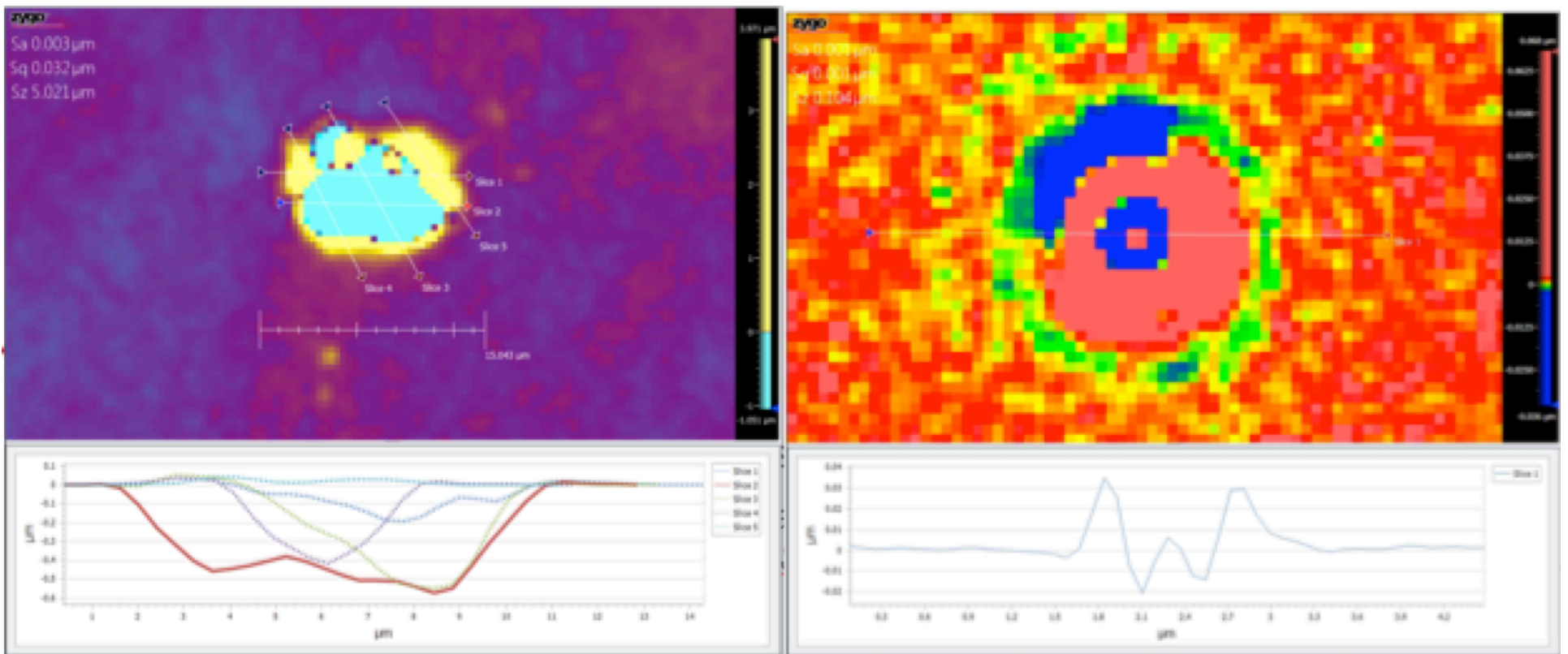
Out of focus LCLS photon  
beam profile in late 2016



Out of focus LCLS photon beam June 2017  
*(images taken in the very first days of operation  
with the machine not perfectly tuned)*

# Wavefront preserving optics development for high power FELs

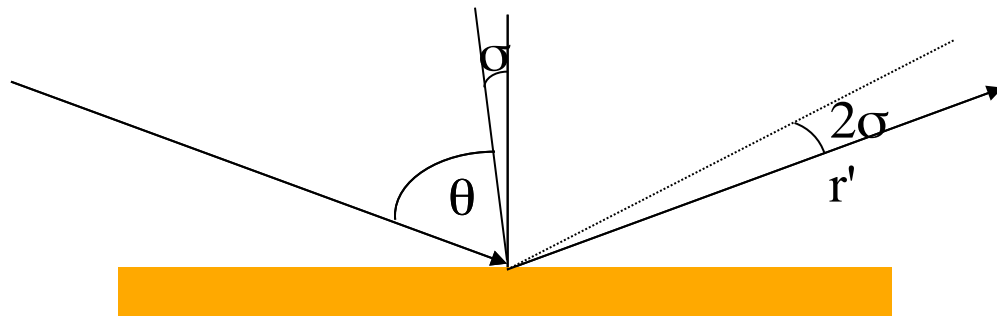
**subtitle: and create a very small spot without destroying  
the mirrors**



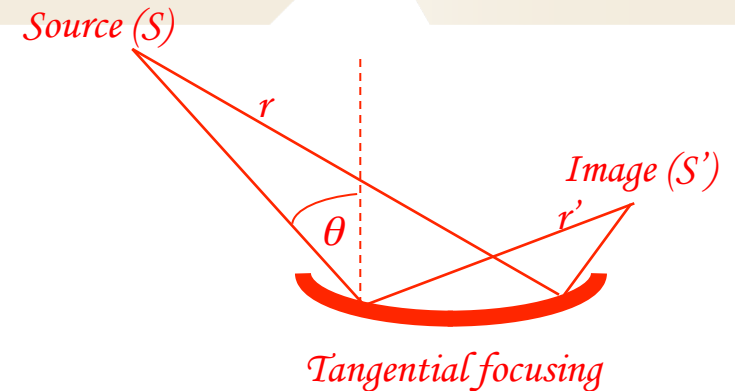
Best spot before cleaning (and wavefront sensor alignment)  $\approx 3 \mu\text{m}$

Measured spot after cleaning (and wavefront sensor alignment)  $\approx 1 \mu\text{m}$

# Grazing incidence optics defect - SLOPE ERRORS



Spot enlargement  $\Delta s' = 2 r' \sigma$



*Tangential focusing*

**M** (magnification) =  $r'/r$



Need a  $1 \mu\text{m}$  spot

→  $r' \approx 1 \text{ m}$

Needed  $\sigma \approx 0.5 \mu\text{rad}$

$$\Delta s' (0.1 \mu\text{m}) = 2 r' (1 \text{ m}) \sigma (0.05 \mu\text{rad})$$

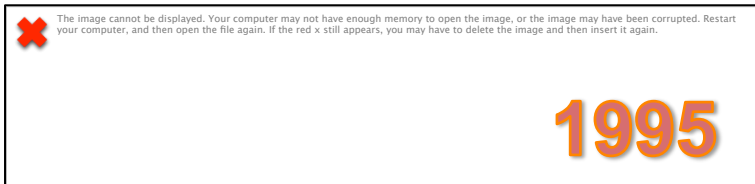
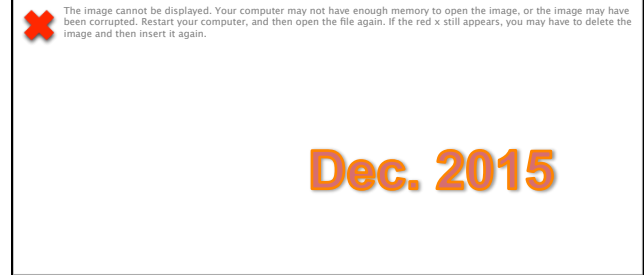


# Understand what you really need

Optical designer in SR are use to specify mirrors in slope. This modus operandi has been transferred to the FELs

Only recently, it has been demonstrated that SHAPE is important, not slope

It was, actually, embedded into a 20 years old precursor article (it was just too advanced, at that time, for the SR needs)



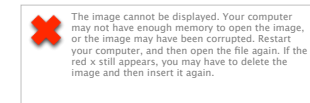
In a **diffraction-limited optic**, with  $W > L$  (classical FEL cases), only shape errors are important and slope errors, in principle, does not play any role in spot enlargement or beam inhomogeneity

System coherence length ( $W$ )

$$W = \frac{\sqrt{2}\lambda}{\Theta \sin \vartheta}$$

Angular radius ( $1/e^2$ )  $\rightarrow$

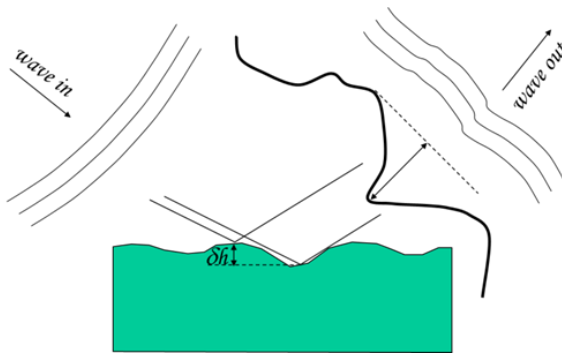
Illuminated part of the mirror  $\rightarrow$



# Shape errors effect

$$\text{Strehl Ratio} \approx e^{-(2\pi\varphi)^2} \approx 1 - (2\pi\varphi)^2$$

The Strehl Ratio (SR) is defined as a ratio of the maximum intensity in the focus, with and without wave front distortions which are introduced by the optics

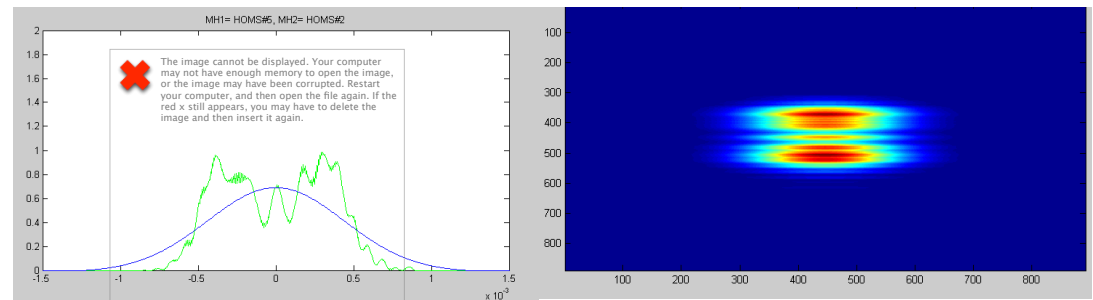
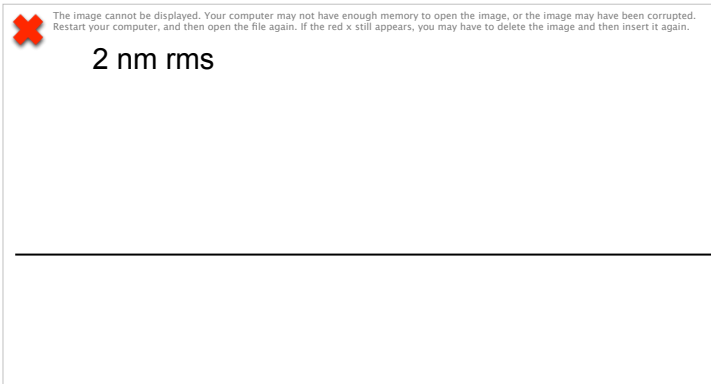


$$\varphi = \frac{2\delta h \sin \vartheta}{\lambda}$$

$\varphi$  is the wave distortion (phase)

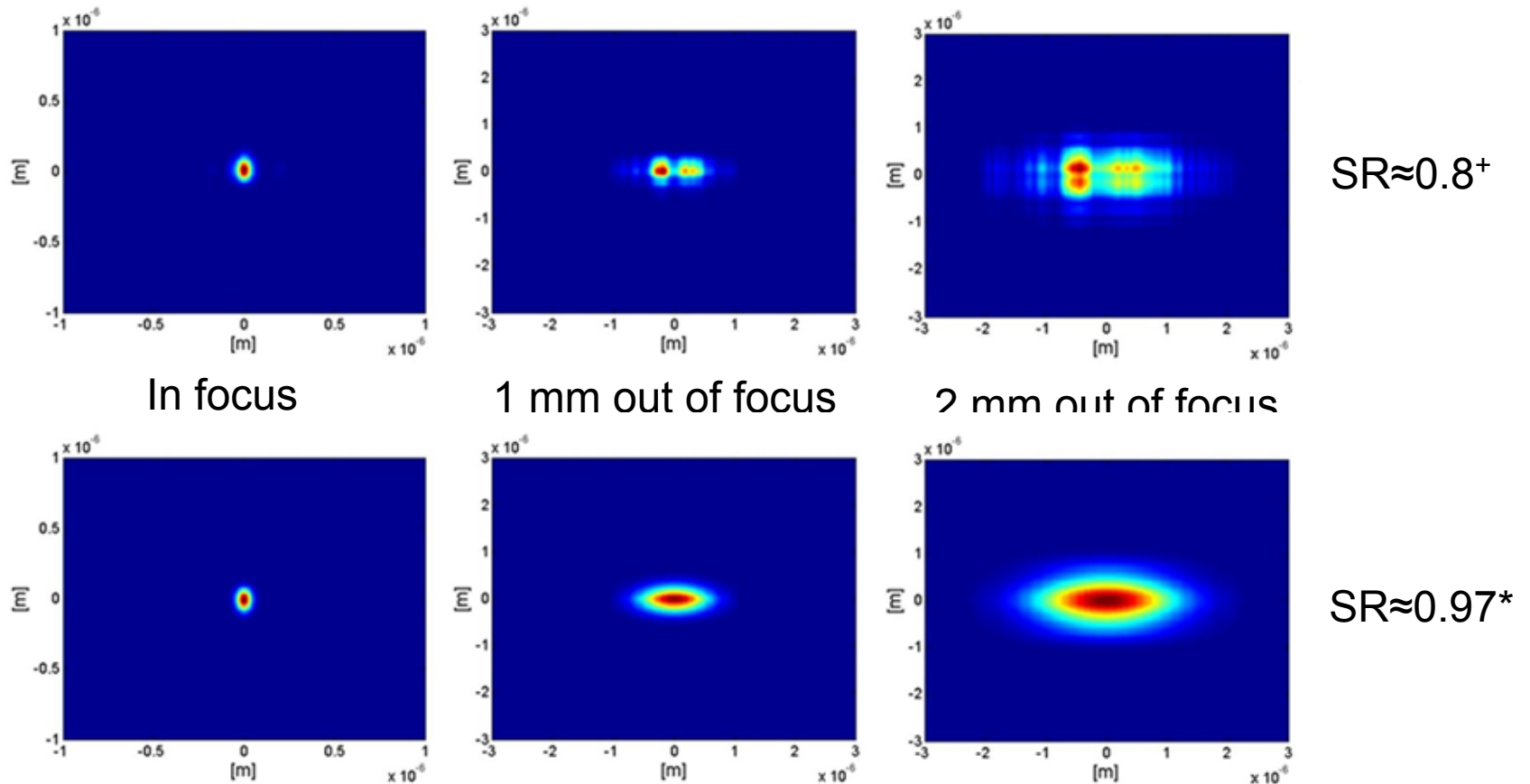
$$\delta h = \lambda \frac{\sqrt{1 - \text{Strehl Ratio}}}{4\pi \sin \vartheta}$$

SR  $\geq$  0.8 (according to the Marechal Criterion) is necessary to have "good" optical system



# Shape errors effect

The Marechal Criterion states that a good optical system has a  $SR \geq 0.8$ ; e.g. In focus: the *Gaussian* spot intensity is  $\geq 0.8$  of the unperturbed *Gaussian* spot intensity



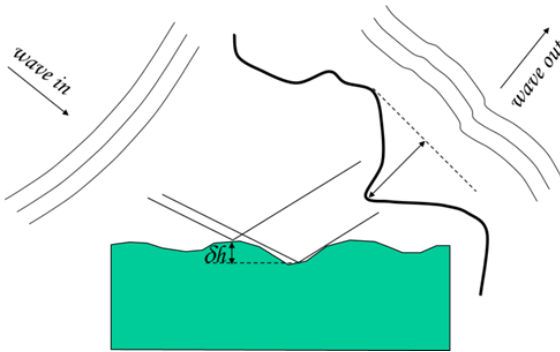
<sup>+</sup> Simulations of 3 mirrors in one direction and 1 in the other for a global SR of 0.8

<sup>\*</sup> Simulation made with state of the art CXI mirrors

## Shape errors effect

$$\text{Strehl Ratio} \approx e^{-(2\pi\varphi)^2} \approx 1 - (2\pi\varphi)^2$$

The Strehl Ratio (SR) is defined as a ratio of the maximum intensity in the focus, with and without wave front distortions which are introduced by the optics



$$\varphi = \frac{2\delta h \sin \vartheta}{\lambda} \quad \varphi \text{ is the wave distortion (phase)}$$

$$\delta h = \lambda \frac{\sqrt{1 - \text{Strehl Ratio}}}{4\pi \sin \vartheta}$$

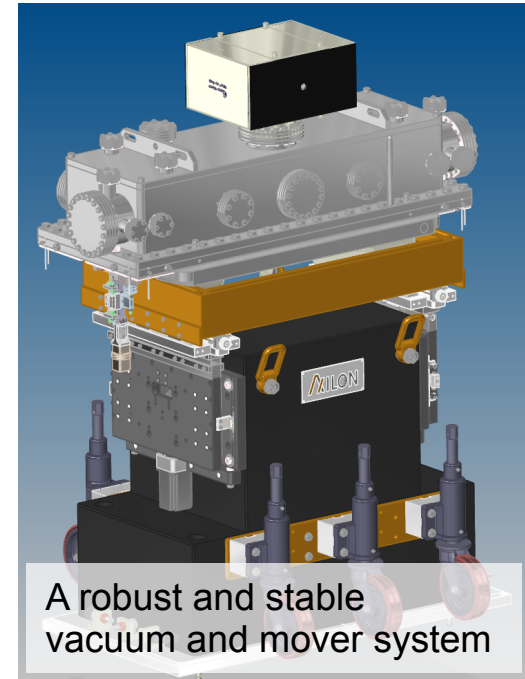
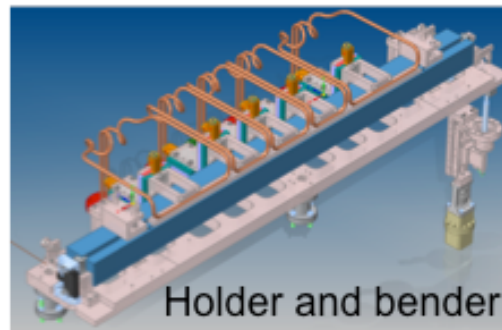
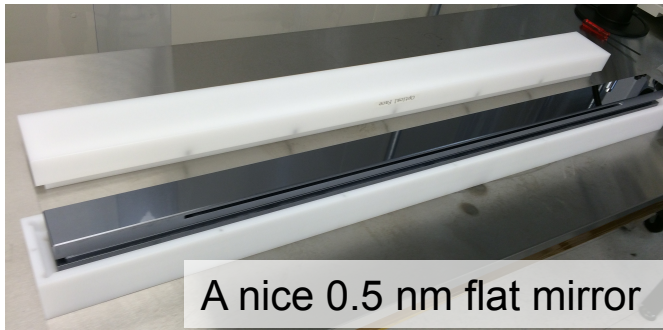
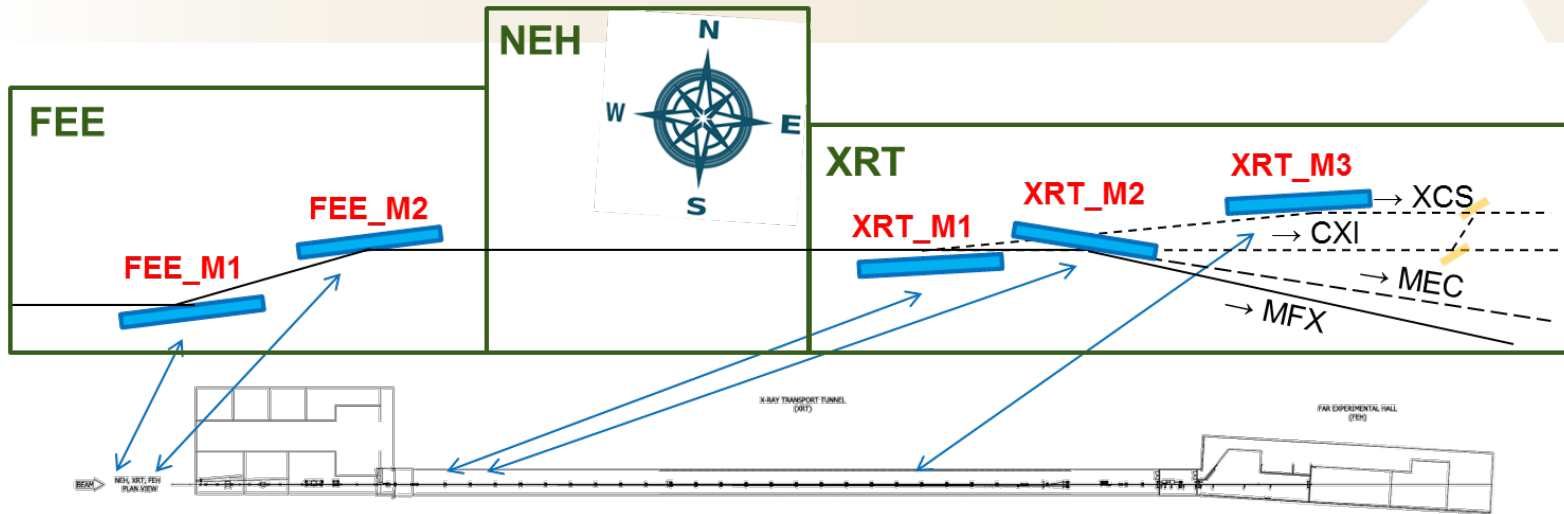
$SR \geq 0.8$  (according to the Marechal Criterion) is necessary to have “good” optical system

**Examples for a SR=0.97:** HXR; 1.35 mrad, 13 keV → **0.56 nm rms**  
 (current LCLS configuration) SXR; 12.0 mrad, 1.3 keV → **0.63 nm rms** (after 3 mirrors)

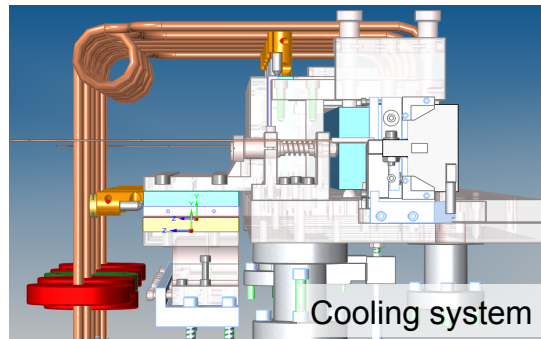
***30 times better than a very good X-ray mirror***

***NOTE: with the mirror installed and under the beam!***

# HOMS (HXR mirror system) upgrade

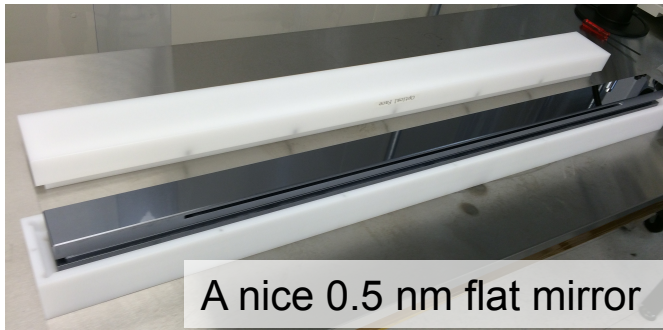
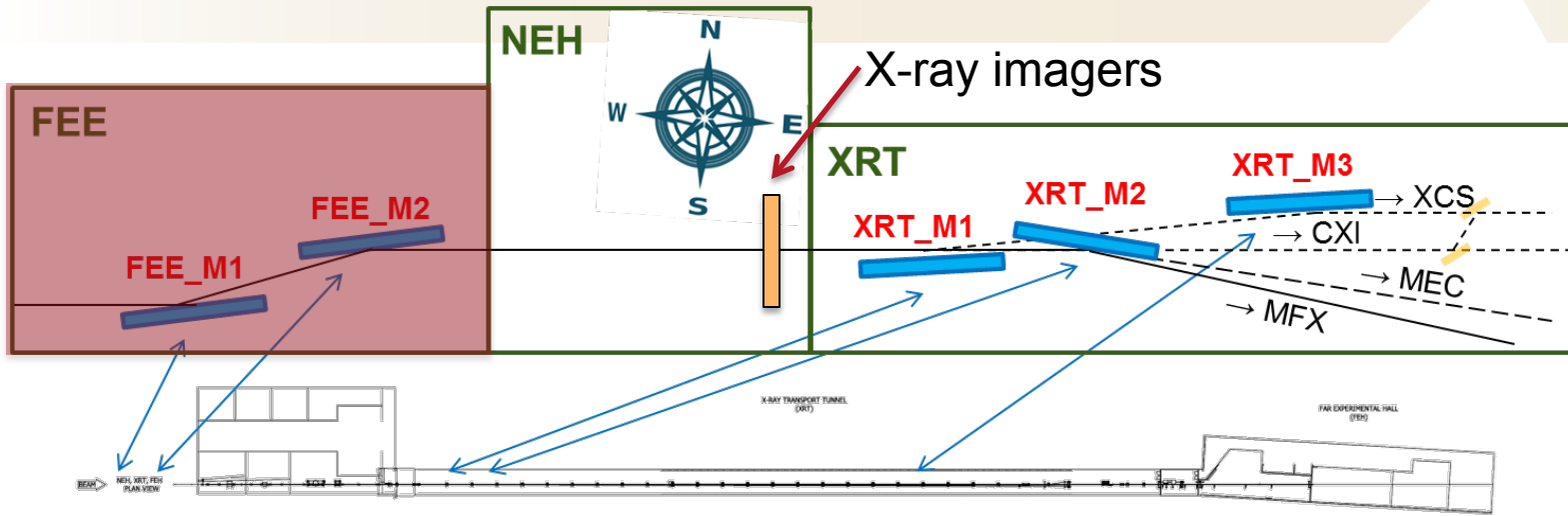


..to what we need to have (< 0.5 nm rms, 2 FWHM acceptance) *with up to 200 W on the mirror*






# Does it work?



$\theta = 1.35$  mrad  
 $\lambda = 0.13$  nm (9500 eV)  
 SR expected (after 2 mirrors)  $> 0.98$

 The image cannot be displayed. Your computer may not have enough memory to open the image, or the image may have been corrupted. Restart your computer, and then open the file again. If the red x still appears, you may have to delete the image and then insert it again.

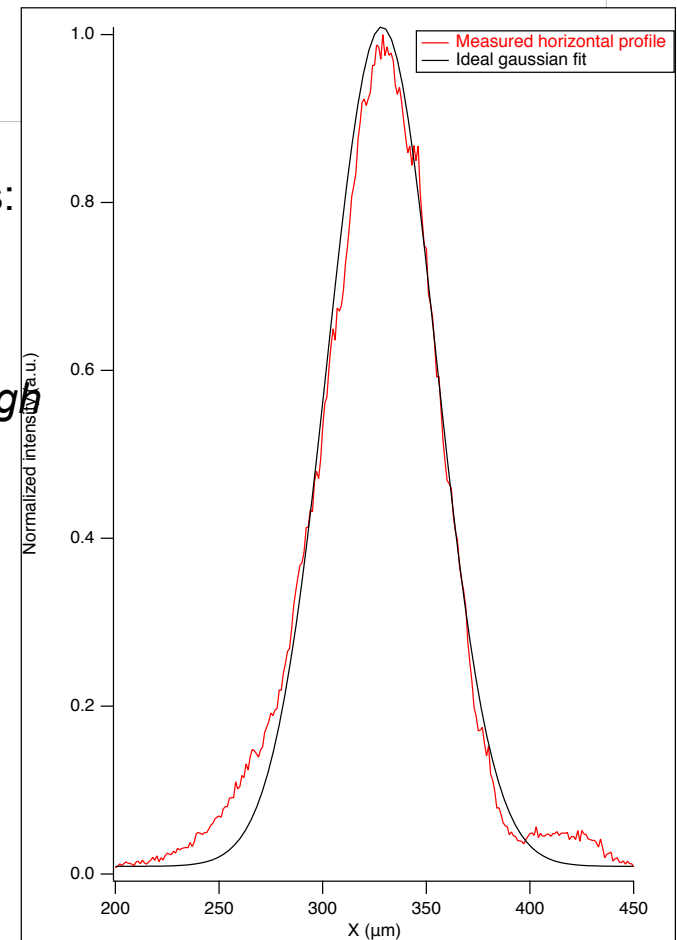
**Mirrors profile**  
 rms shape error  $< 0.5$  nm

# Measured spot (out of focus 9.5 keV)

✘ The image cannot be displayed. Your computer may not have enough memory to open the image, or the image may have been corrupted. Restart your computer, and then open the file again. If the red x still appears, you may have to delete the image and then insert it again.

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Potential source of errors:  
Source inhomogeneity?  
*Maybe (not measured)*  
Mirror clamping?  
*Maybe (unlikely at this high frequency)*  
Mirror deterioration?  
Coating inhomogeneity?



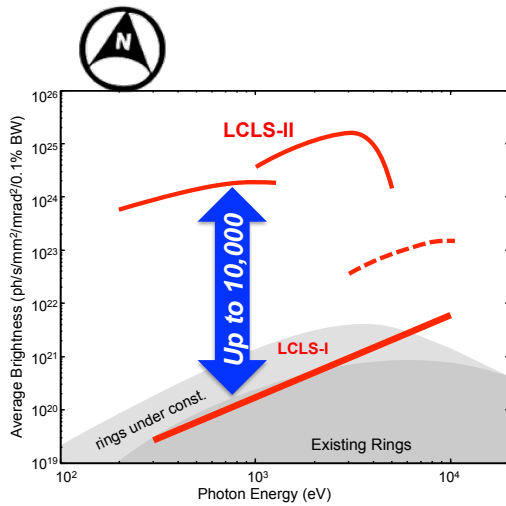
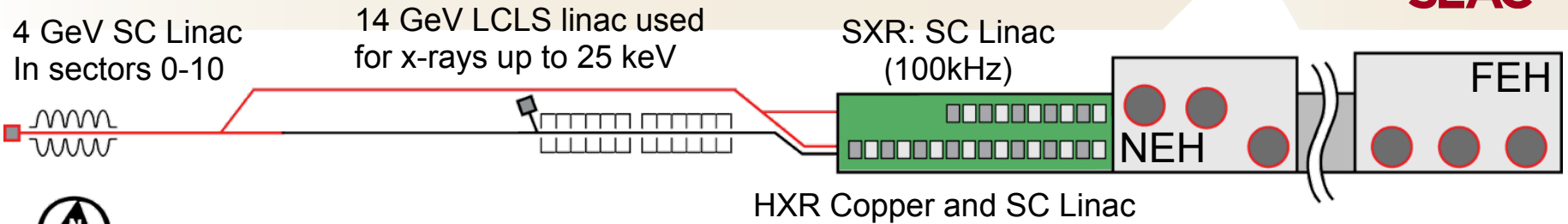
SR expected (after 2 mirrors) > 0.98

SR measured  $\approx$  0.965

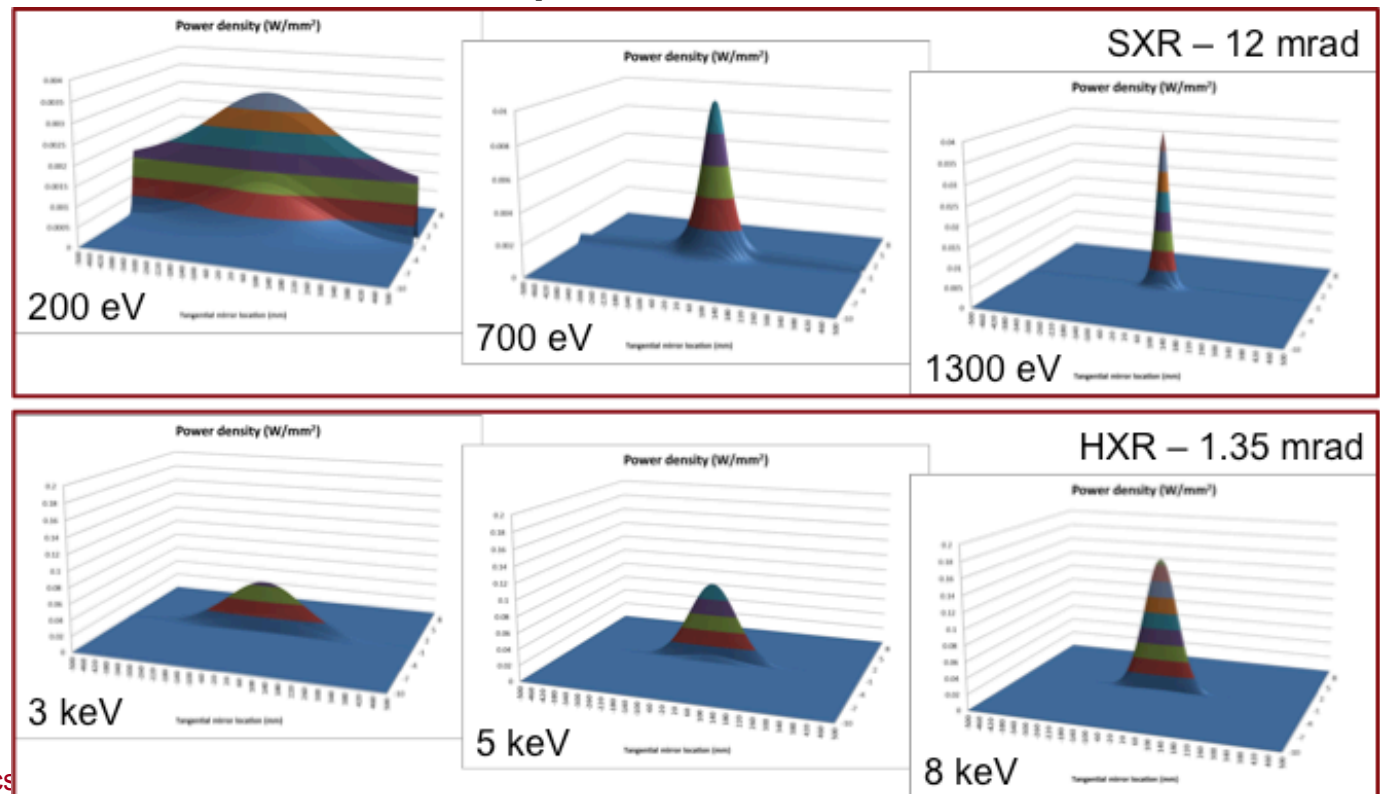
*1 nm rms shape errors needed to have a SR of 0.965*

# LCLS - II

SLAC

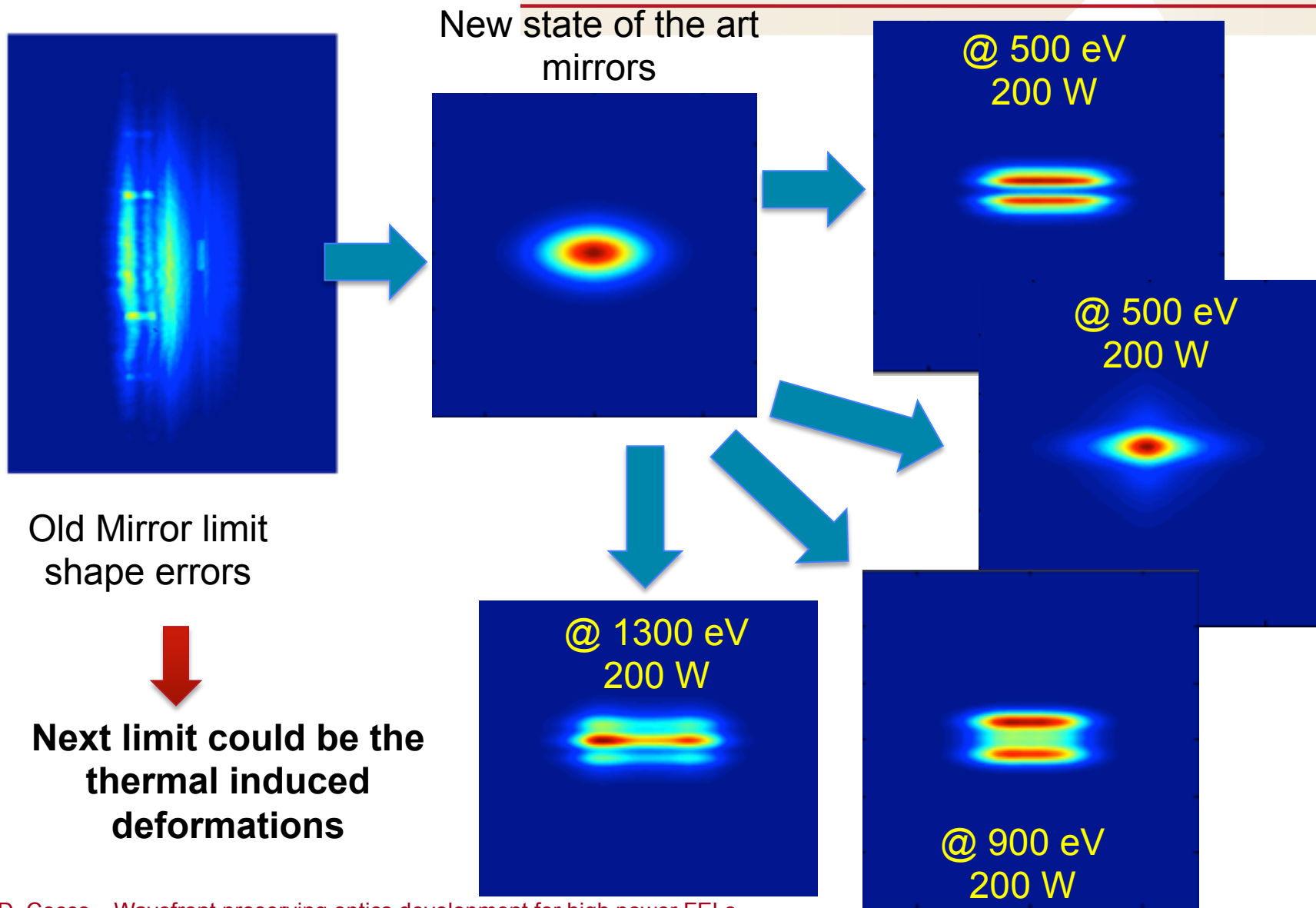


Wide energy range leads to a highly variable beam footprint and power absorbed



From the current  
2-300 mW to up to  
600 W on the optics

# Out of focus beam profile



# Wavefront preserving mirrors – DOE/BES ADR project

SLAC

## WAVEFRONT PRESERVING MIRRORS – ABSTRACT

Daniele Cocco, SLAC National Accelerator Laboratory (Principal Investigator)

Lahsen Assoufid, Argonne National Laboratory (Co-Investigator)

Kenneth Goldberg, Lawrence Berkeley National Laboratory (Co-Investigator)

Mourad Idir, Brookhaven National Laboratory (Co-Investigator)

### Abstract

This proposal brings together teams from the four major, large scale facilities operated under the auspices of the Department of Energy, Basic Energy Science; ..... The development of a novel room-temperature mirror cooling system with in-situ, at-wavelength testing, and the study of non-invasive wavefront sensing are aimed at preserving the wavefront and the beam quality of **Free Electron Lasers (FELs) and Diffraction Limited Storage Rings (DLSR)**.

- 2 years project:
- Deliverables:
  - **SLAC:** Development and demonstration of the novel cooling scheme
  - **BNL:** Implementation of an “invasive” wavefront sensor to test REAL sustaining 50-100 W
  - **LBNL:** Study of “non invasive” beam diagnostics (WS) for SXR
  - **ANL:** Study of “non invasive” beam diagnostics (WS) for HXR





# REAL (Resistive Element Adjustable Length) Cooled Optics



Copper tube and blade

FEL Beam footprint regions

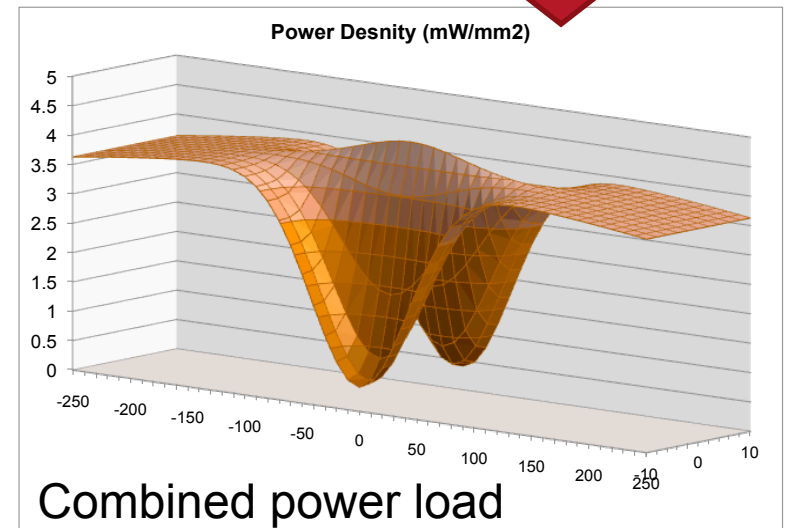
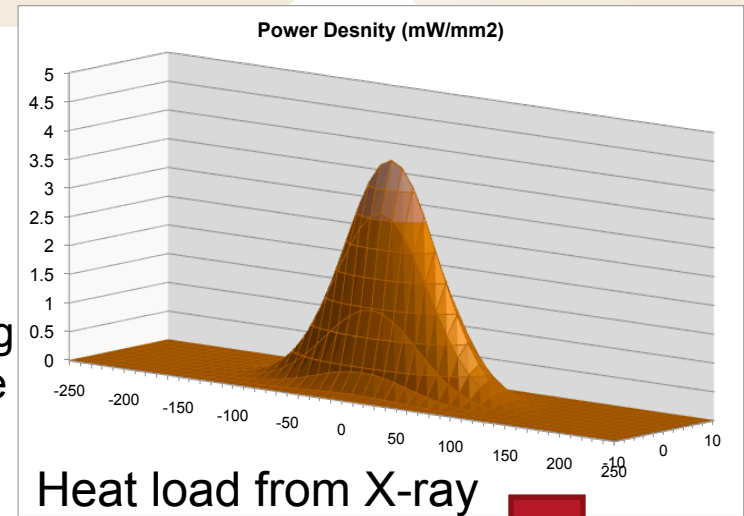
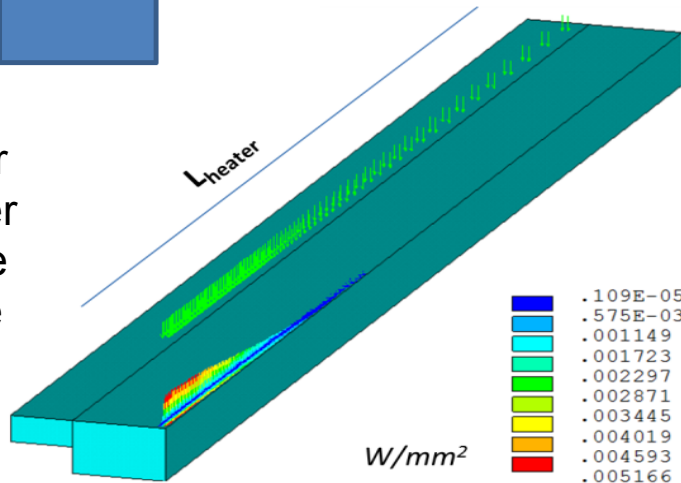
1) Add to the existing fins, used to cool the mirror, some resistive heaters

Gallium-indium eutectic

FEL power

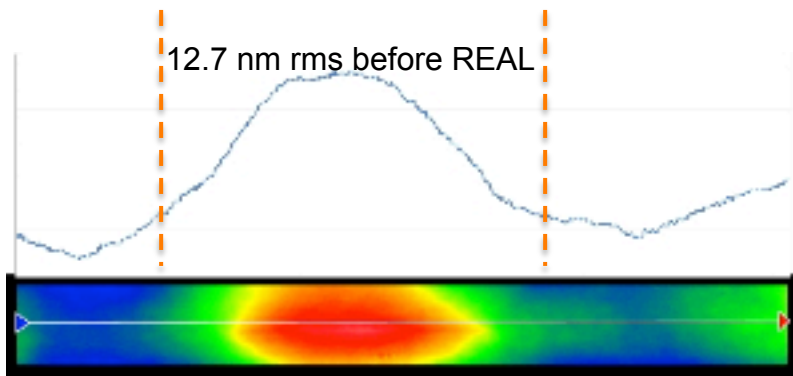
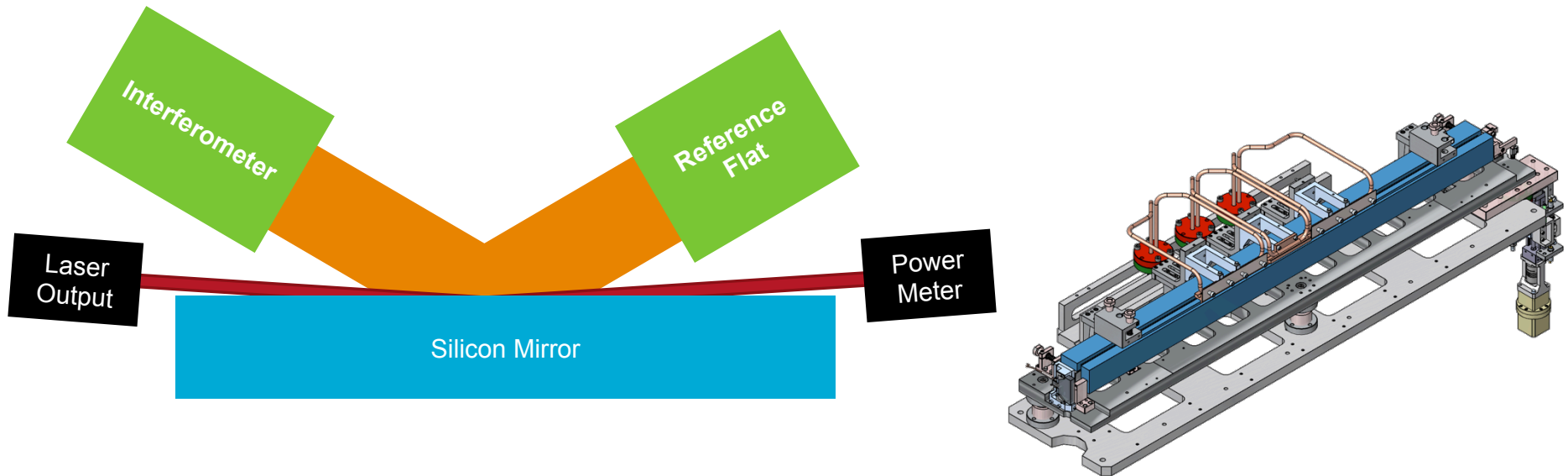
Silicon mirror cross section

2) Apply the proper power to the proper heaters to equalize deformation on the mirror

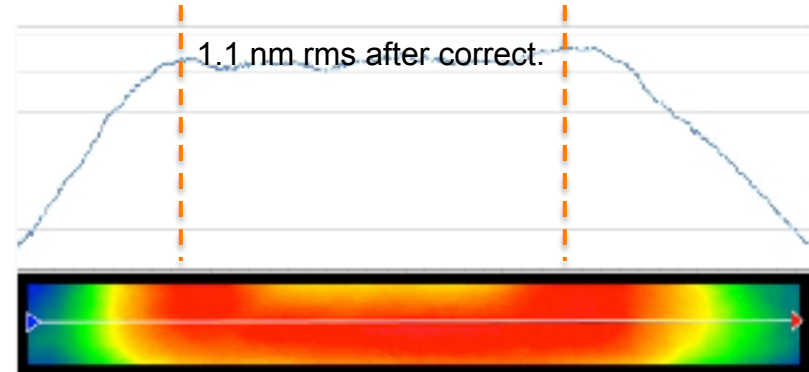


# REAL test

Metrology measurements - 2D map and central line profile ( $\approx 12$  W absorbed)

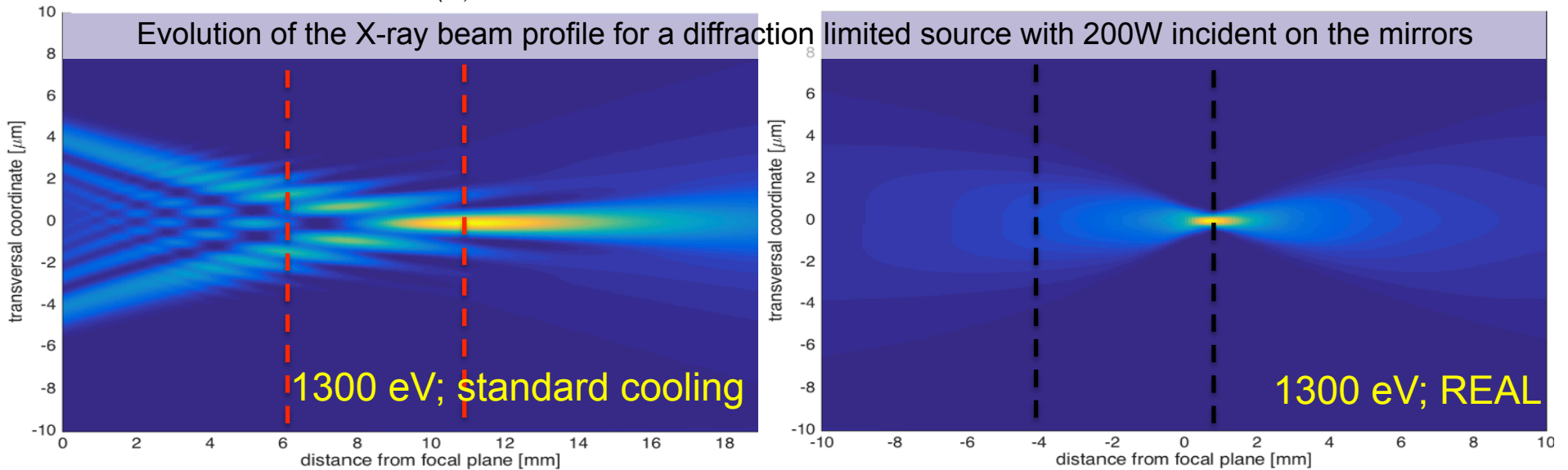
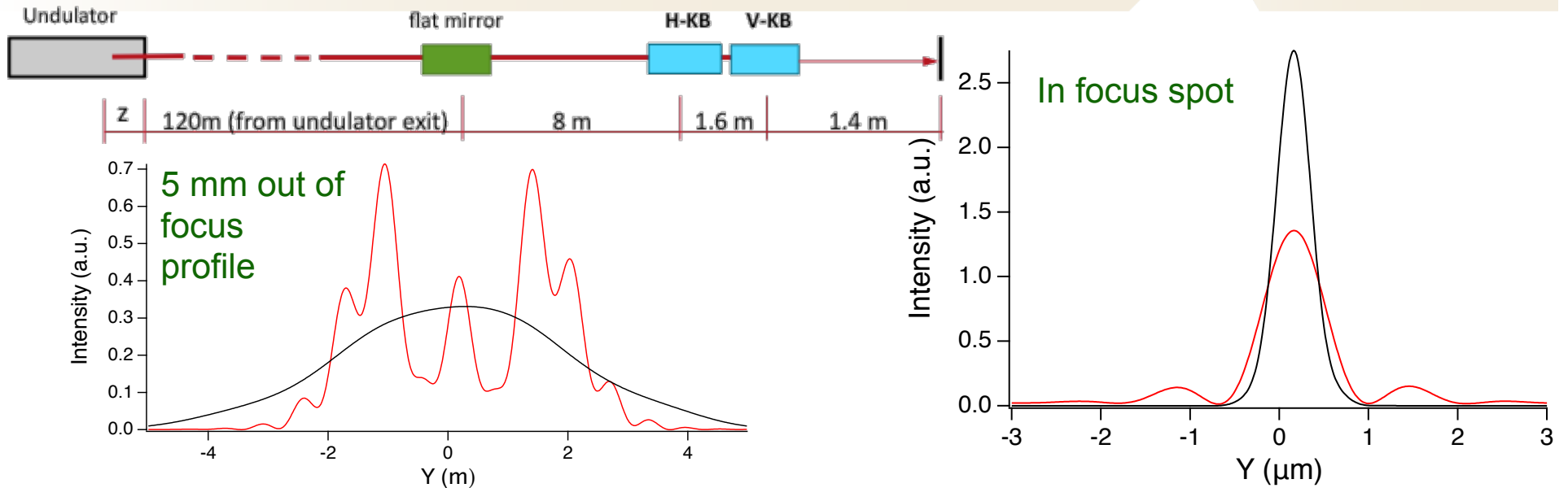


Heat Load induced by an IR laser (15W)



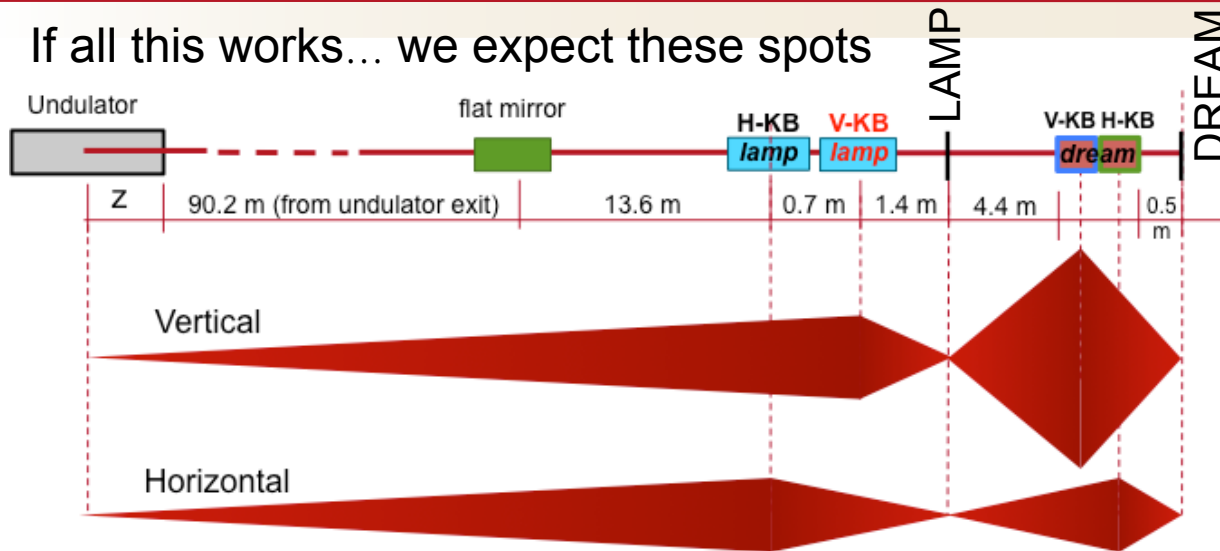
Combined effect (REAL + heat Load)

# Expected performance improvement - a REAL example

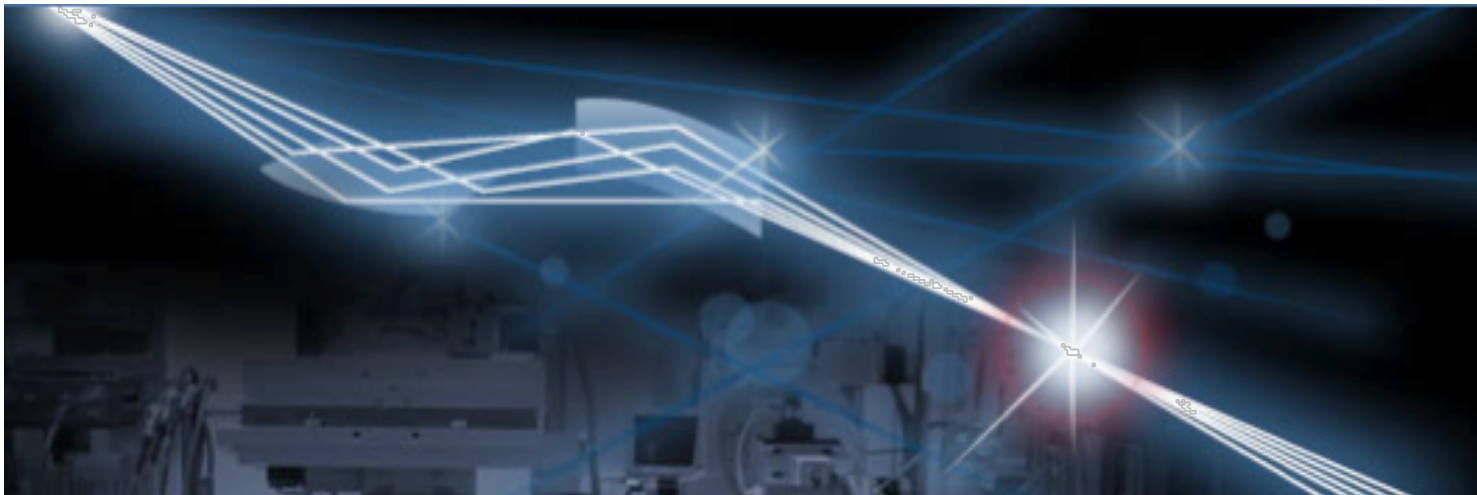


# DREAM and LAMP

If all this works... we expect these spots

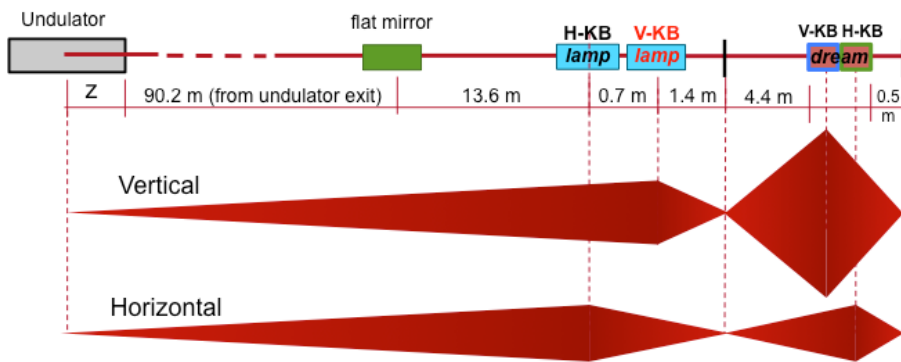


Possibility to run 2 experiments in series  
LAMP mirrors – bendable to optimize the focal spot in both experimental chambers



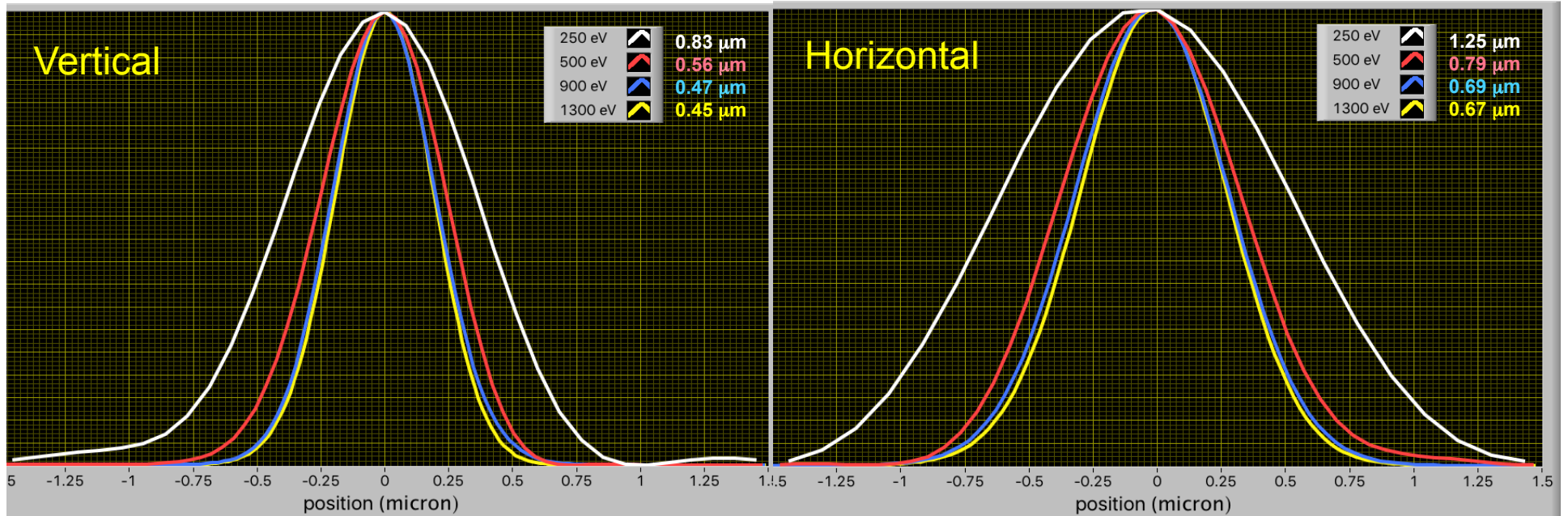
# DREAM and LAMP (expected performance)

If all this works... we expect these spots



Possibility to run 2 experiments in series  
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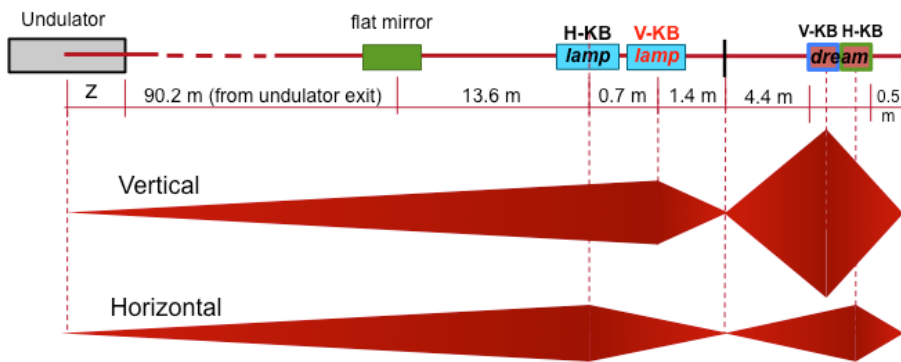
$6 \times 10^{19} \text{ W/cm}^2$  @ 900 eV with 2 mJ pulse





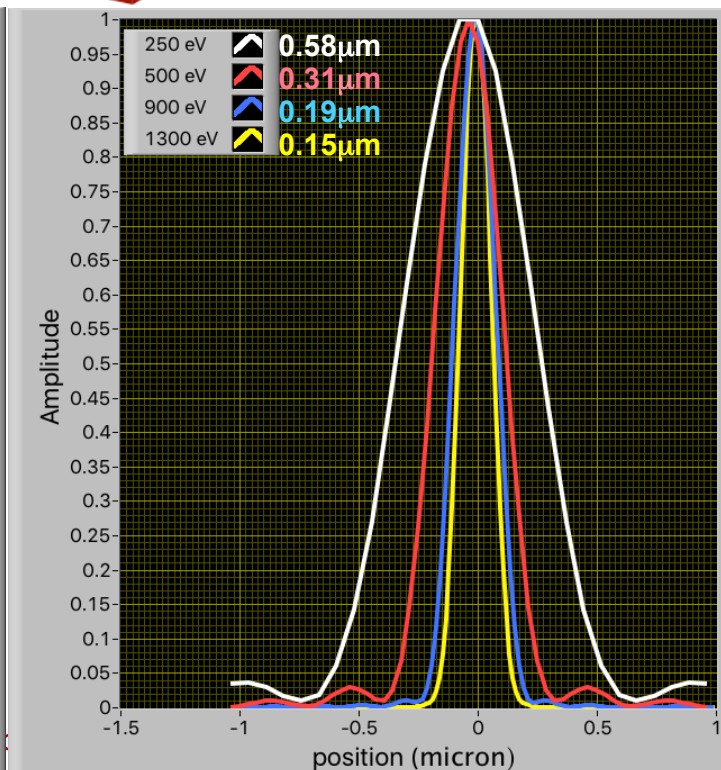
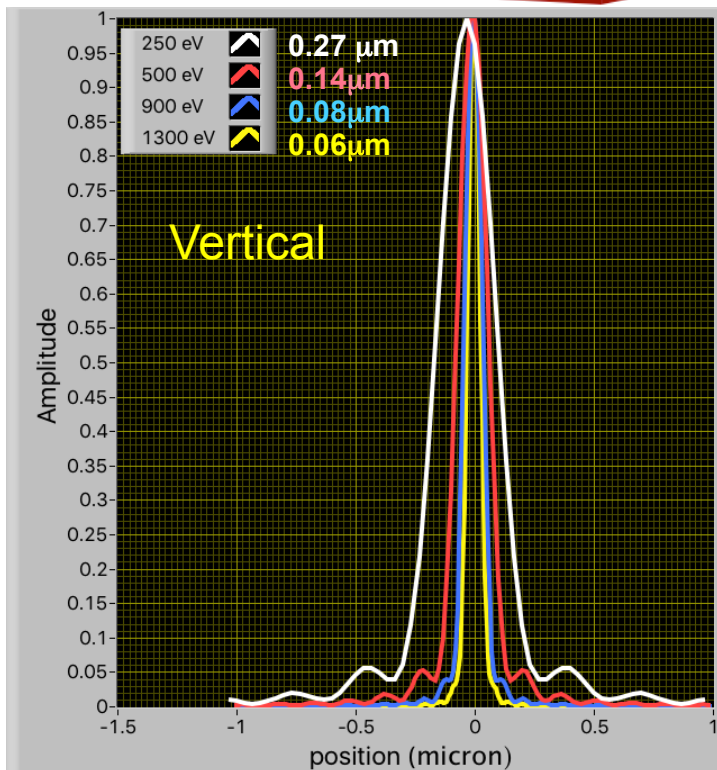
# DREAM and LAMP (expected performance)

If all this works... we expect these spots



Possibility to run 2 experiments in series  
LAMP mirrors – bendable to optimize the focal spot in both experimental chambers

$1.5 \times 10^{21} \text{ W/cm}^2$  @ 1300 eV with 2 mJ pulse

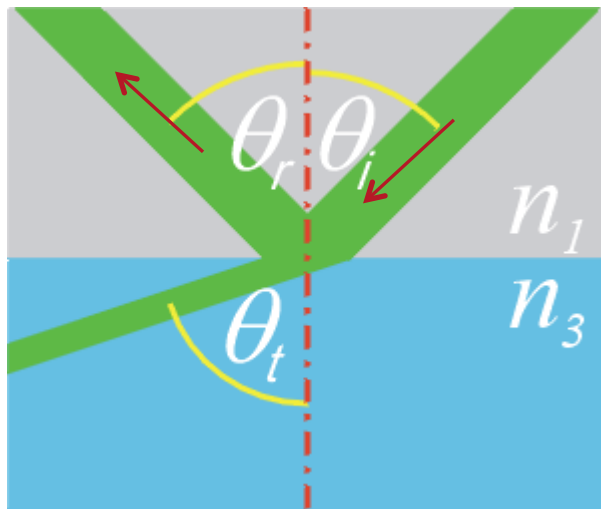


$> 10^{22} \text{ W/cm}^2$   
1300 eV  
12 mJ pulse  
(possible with LCLS II)  
Sub 10 fsec pulse

CAN WE?

# Optical surface damage

Above the grazing critical angle



The non reflected energy is absorbed (1/e) in  $d \ll$

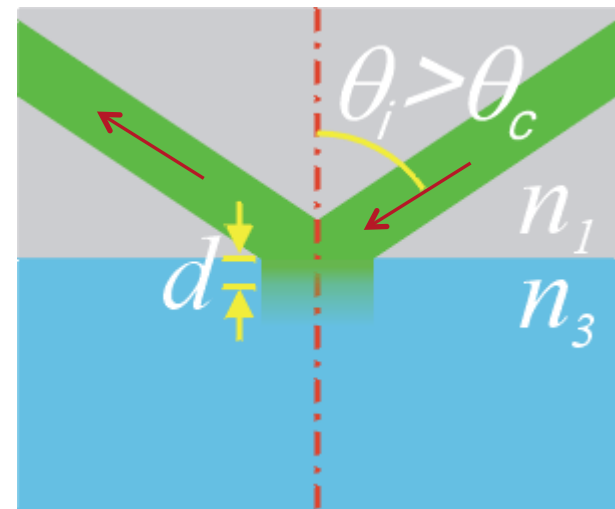
$$d = \frac{\lambda \xi}{4\pi\beta}$$

$$\xi = \sqrt{\frac{\sin^2 \theta - 2\delta + \sqrt{(\sin^2 \theta - 2\delta)^2 + 4\beta^2}}{2}}$$

$$n = 1 - \delta - i\beta$$

$$\delta = \frac{Ne^2 \lambda^2}{2\pi mc^2}$$

Below the grazing critical angle



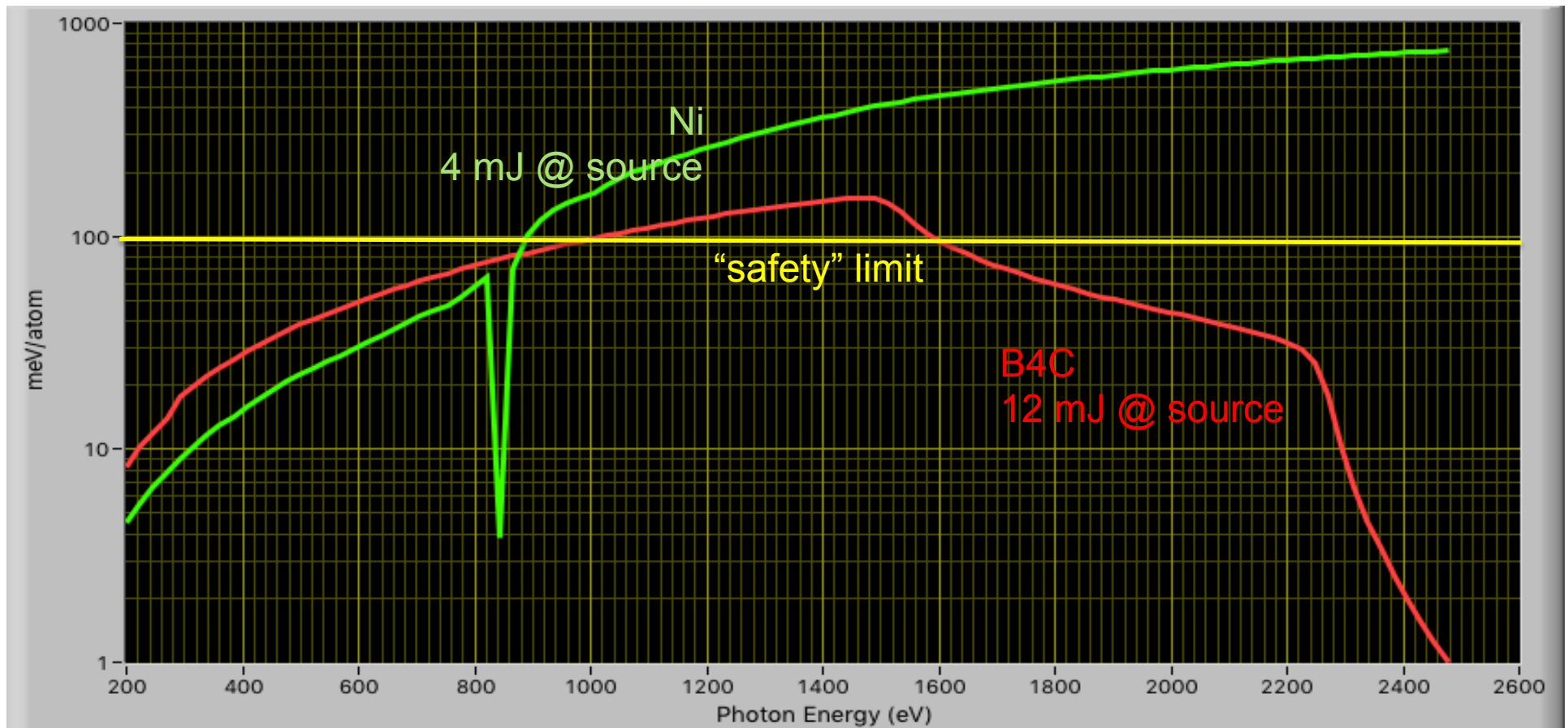
- R=reflectivity
- P=pulse power
- $\theta$ =angle of incidence
- r=source distance
- $\sigma$ =source divergence
- $\rho$ =atomic density

$$Aborbed \ Energy_{ATOM} = \frac{(1-R)P \sin \vartheta}{r \sigma_x \sigma_y d \rho}$$

Ideal coating should have a large penetration depth (light materials) and good reflectivity (usually associated with heavy materials)

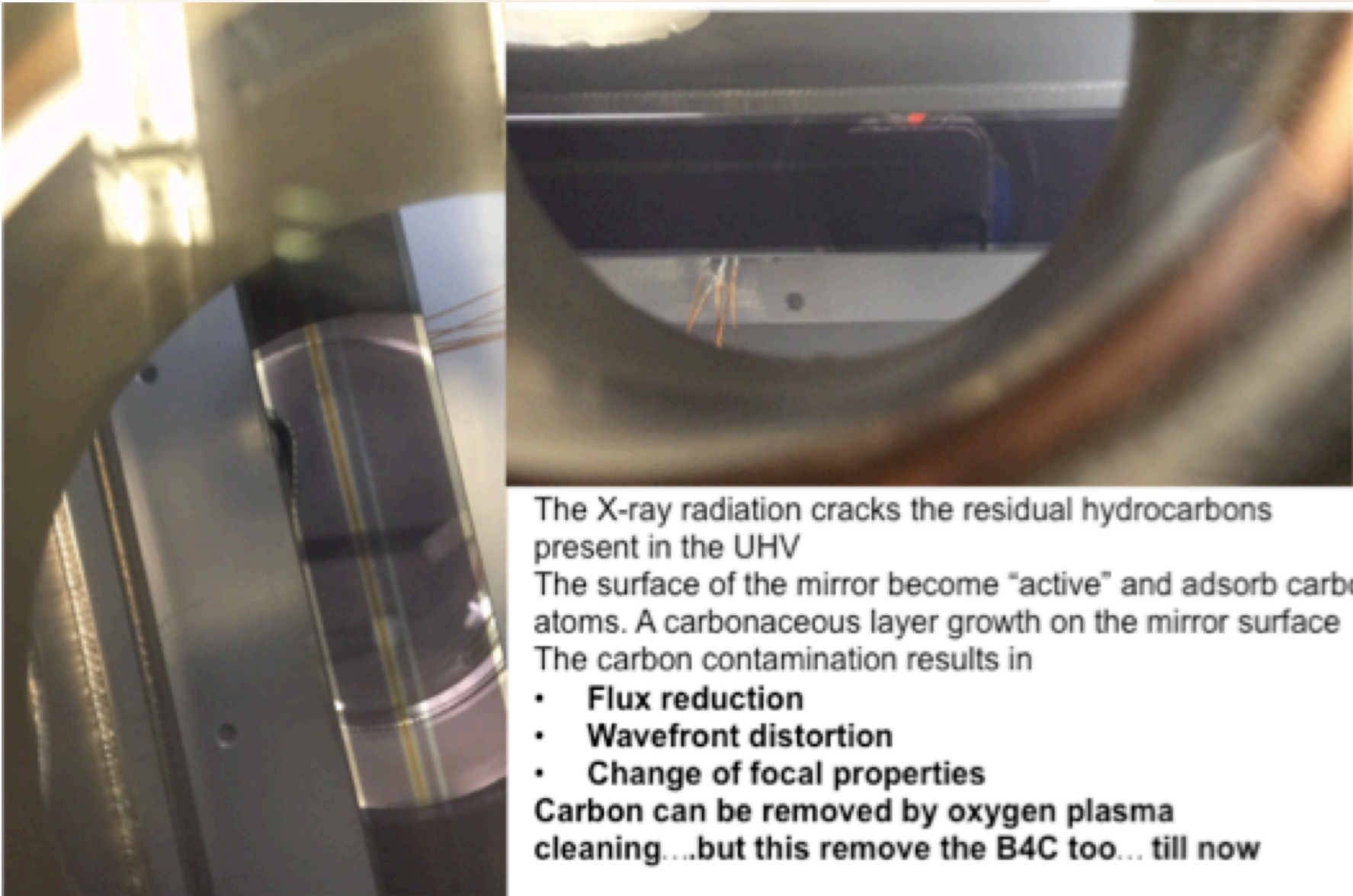
# DREAM (21 mrad) – damage threshold

- Need to work at 21 mrad to collect the entire beam
- $B_4C$  as the reflective coatings works from 5-600 to 1600 eV up to 12 mJ pulse energy
- Ni works up to 700 eV and up to 4 mJ pulse energy



Let's use B4C... not so quickly

## There is a problem.....



The X-ray radiation cracks the residual hydrocarbons present in the UHV

The surface of the mirror become "active" and adsorb carbon atoms. A carbonaceous layer growth on the mirror surface

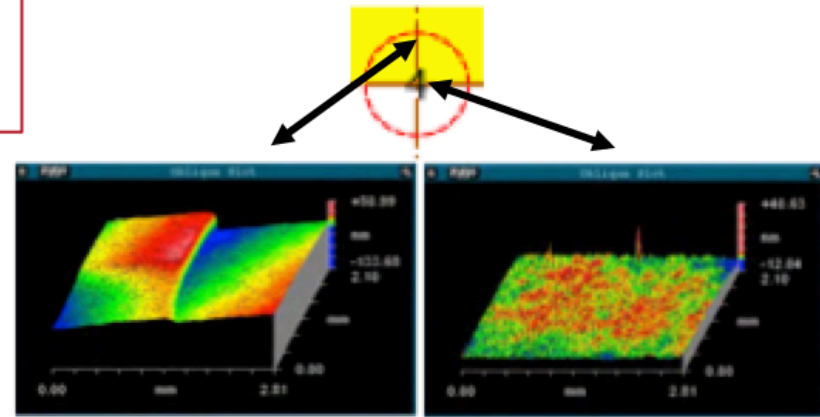
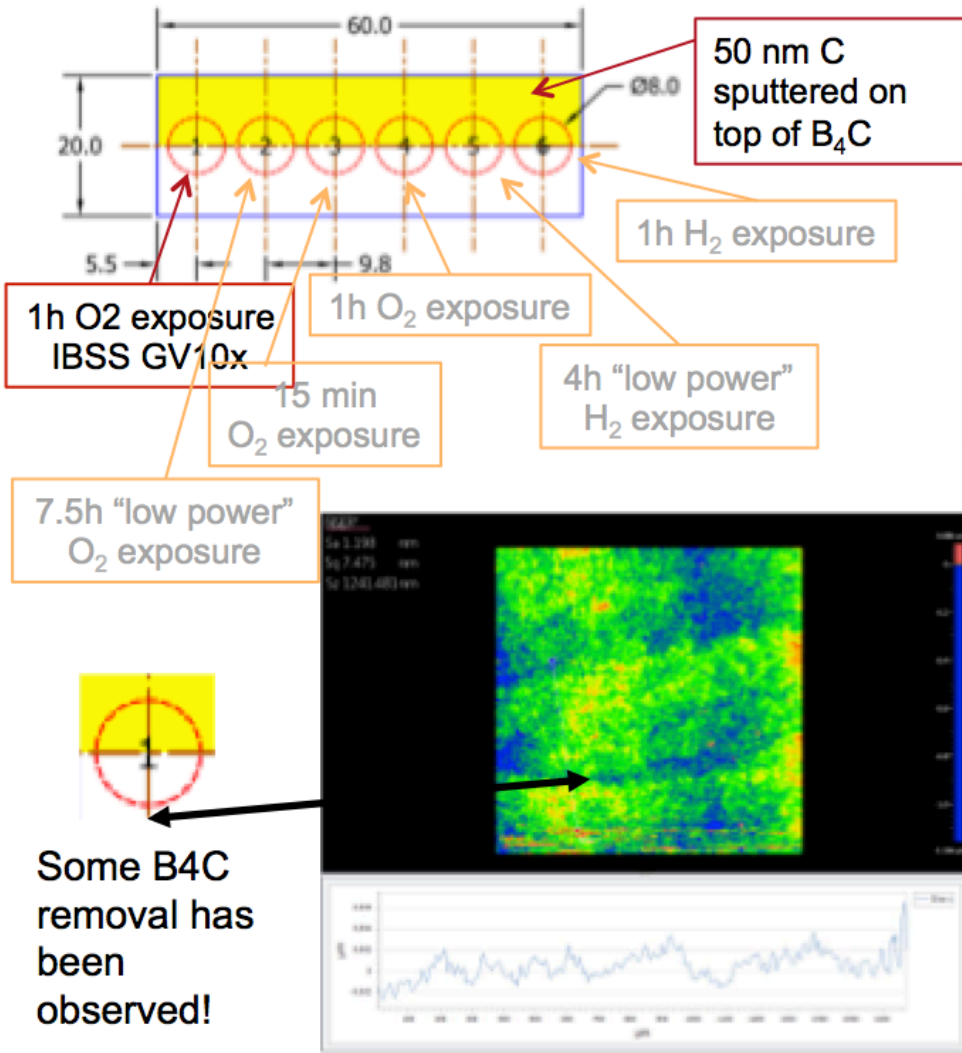
The carbon contamination results in

- **Flux reduction**
- **Wavefront distortion**
- **Change of focal properties**

**Carbon can be removed by oxygen plasma cleaning....but this remove the B4C too... till now**

# B<sub>4</sub>C cleaning

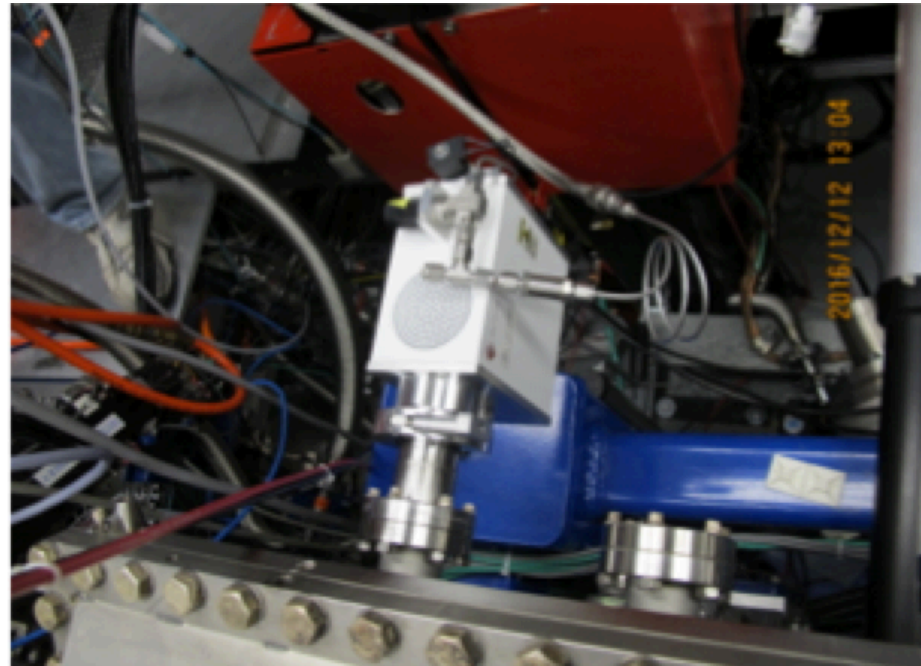
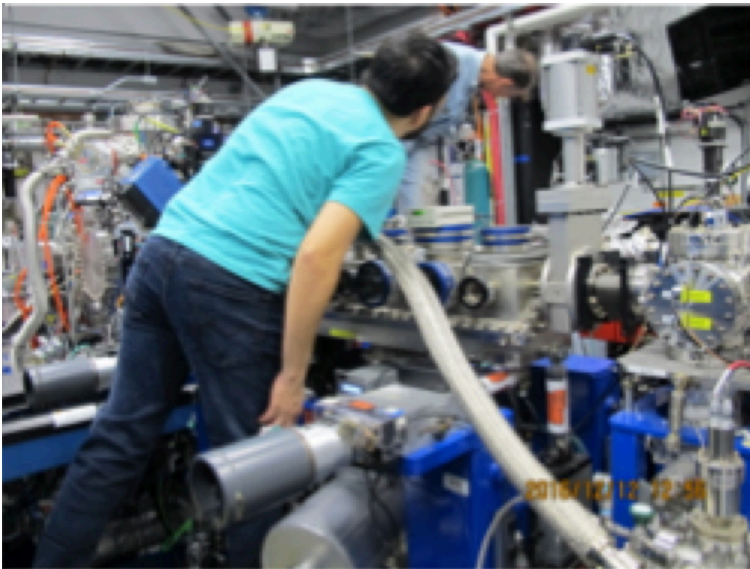
Test sample: 50 nm B<sub>4</sub>C coating on Silicon



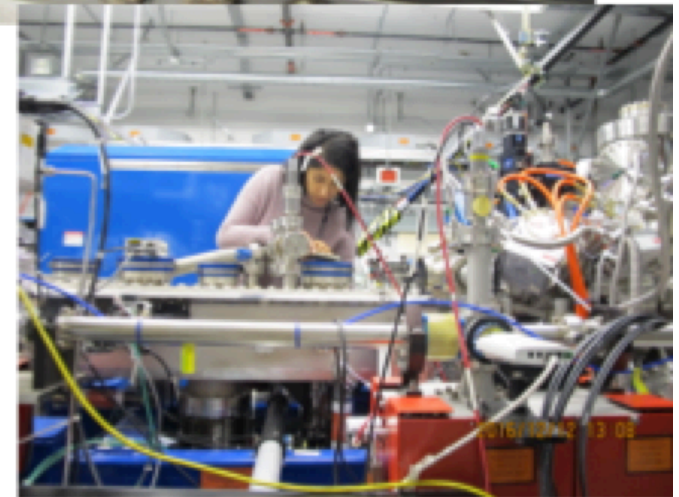
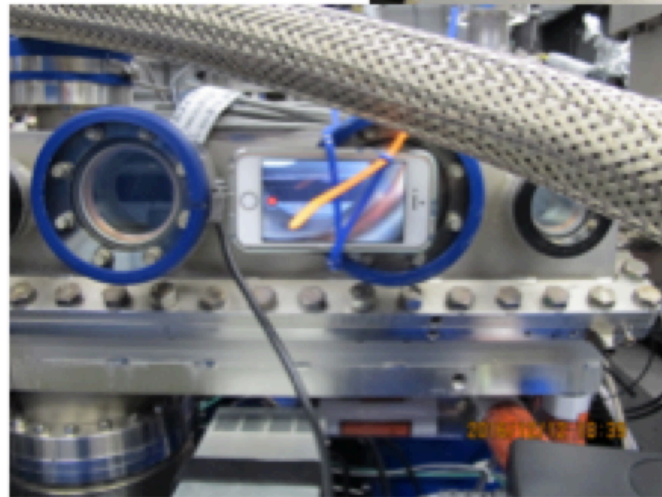
On zone 4 there is an apparent full removal of Carbon contamination with no apparent increase of roughness



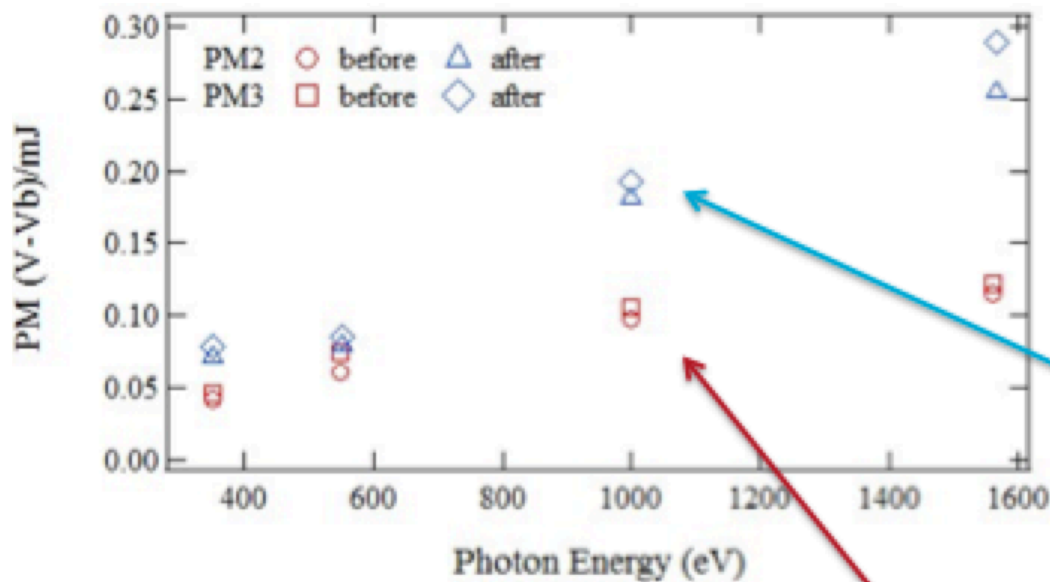
# B4C coated KBs cleaning



Despite some risk we decided to proceed with the cleaning using an iPhone to track the cleaning evolution and visual inspection to decide when we are done

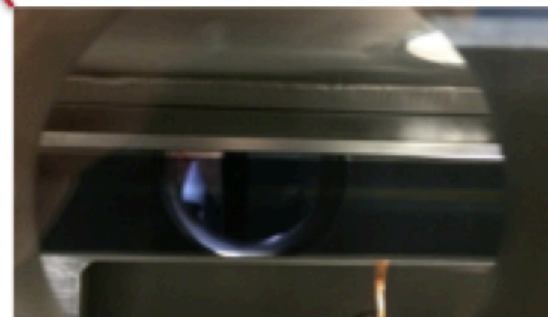
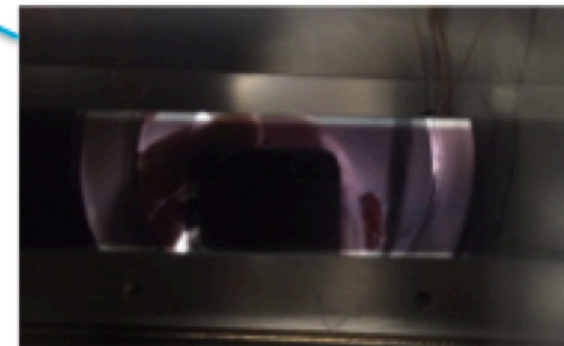


# B4C coated KBs cleaning

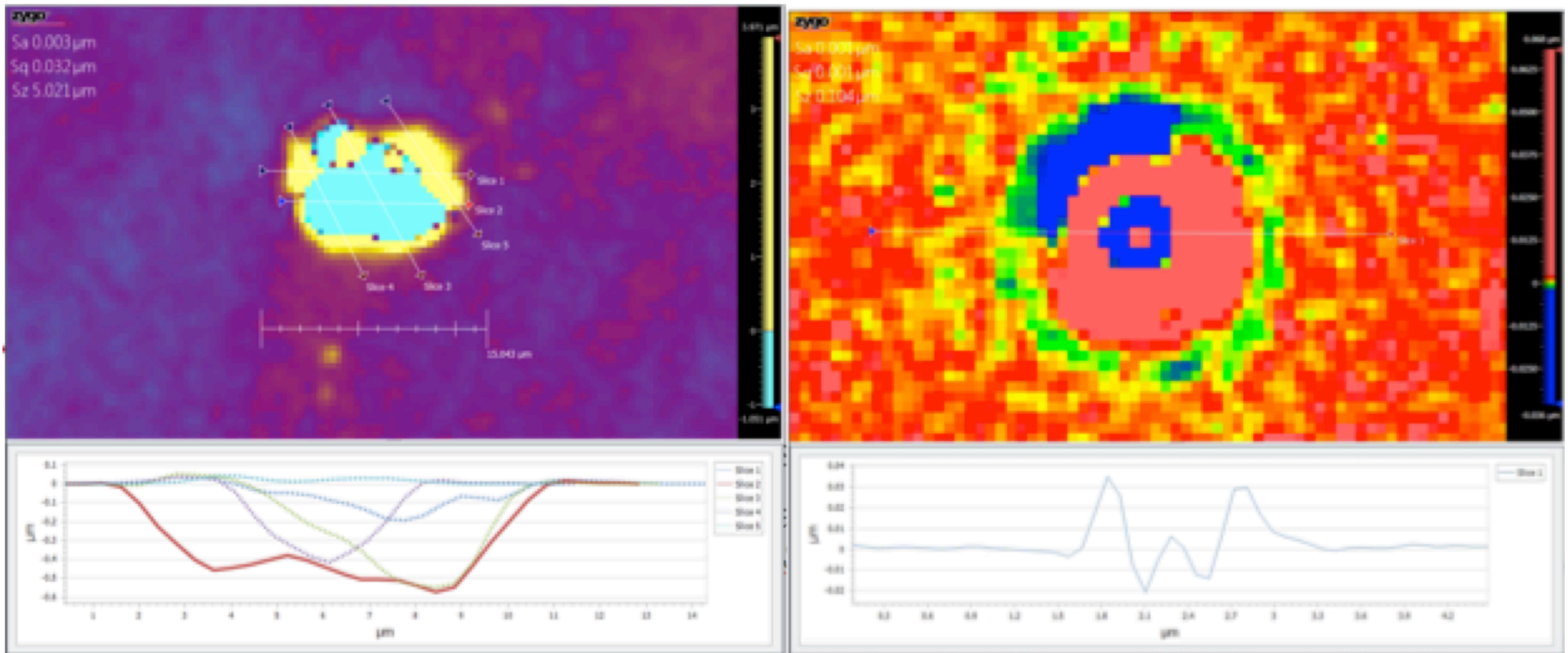


GAIN  
350 eV: 1.51 → Contamination footprint narrower than the beam  
550 eV: 1.19 → Some residual Oxygen contamination  
1000 eV: 1.77 } Imply a very rough contamination layer  
1560 eV: 2.67 }

900 eV has been the most used photon energy and 500 the lowest  
Most of the 300 eV beam sees a “clean mirror”  
(a donat-like profile has been observed out of focus at low energy)



# Improvement in spot profile



Best spot before cleaning (and wavefront sensor alignment)  $\approx 3 \mu\text{m}$

Measured spot after cleaning (and wavefront sensor alignment)  $\approx 1 \mu\text{m}$

## With High Rep Rate Machine...

Growth:

HXR 2 nm *measured* in 6 years @120 Hz

Maximum tolerable thickness: 5-10 nm

@ 100 kHz one should have 10 nm in 2 weeks!

SXR 40-50 nm estimated from cleaning in 6 years @120 Hz

Maximum tolerable < 5 nm

@ 100 kHz one should have 5 nm in 6 hours!

Luckily the process is slow so, high rep rate will not act so drastically but, will help the growth. It is expect needing a cleaning process every 6 months

*Mitigation: Procure large mirrors and use a fresh part of the coating*

*Improve of one order of magnitude the vacuum level*



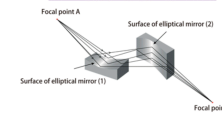
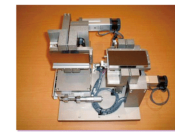
# 7 nm spot @ SPRING 8 - Japan

Step to reach such a small focus (Yamauchi; Ishikawa)

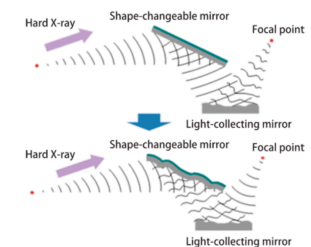
1) Have a 1 Km beamline on a stable synchrotron



2) Make a 2 steps process with very small mirrors



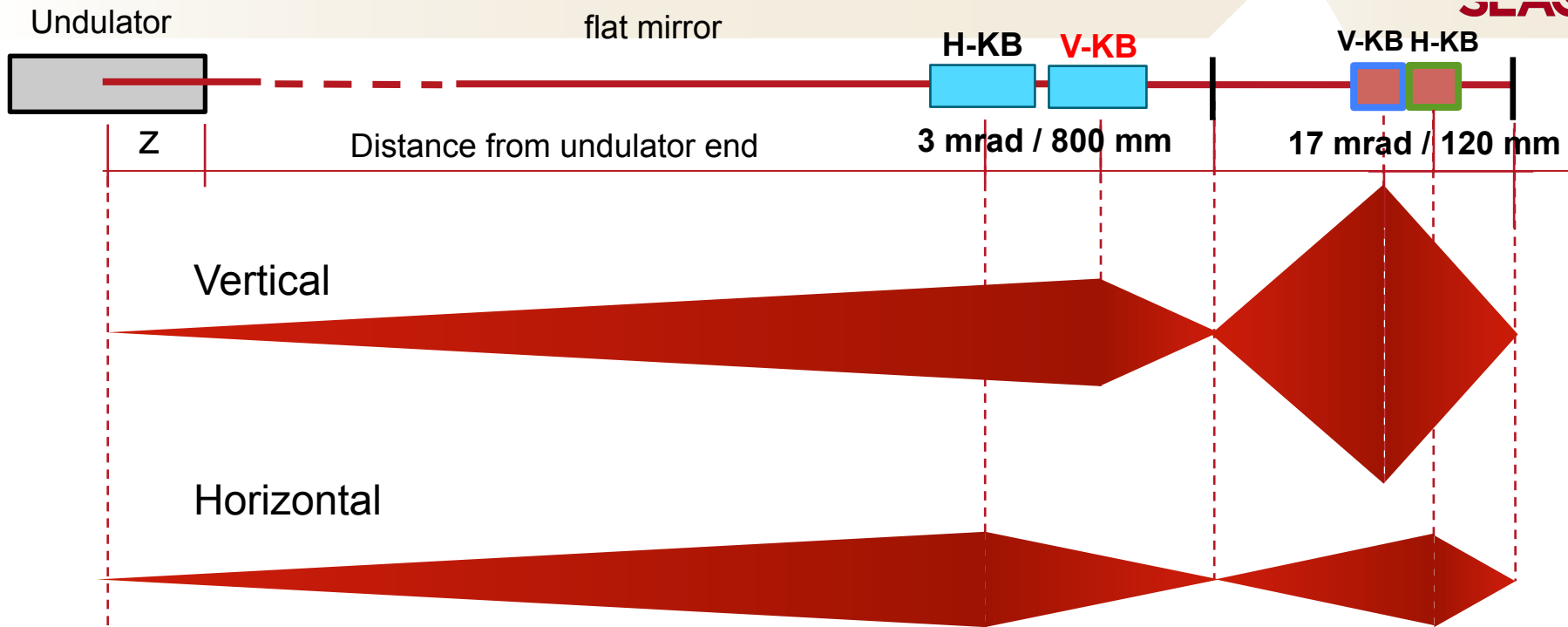
3) Use of large angle of incidence multilayer mirrors and correcting optics



Not all these options are compatible with the length of the experimental halls and high power FEL beam

# TW beamline Layout 4 mirrors @ 8 keV

SLAC



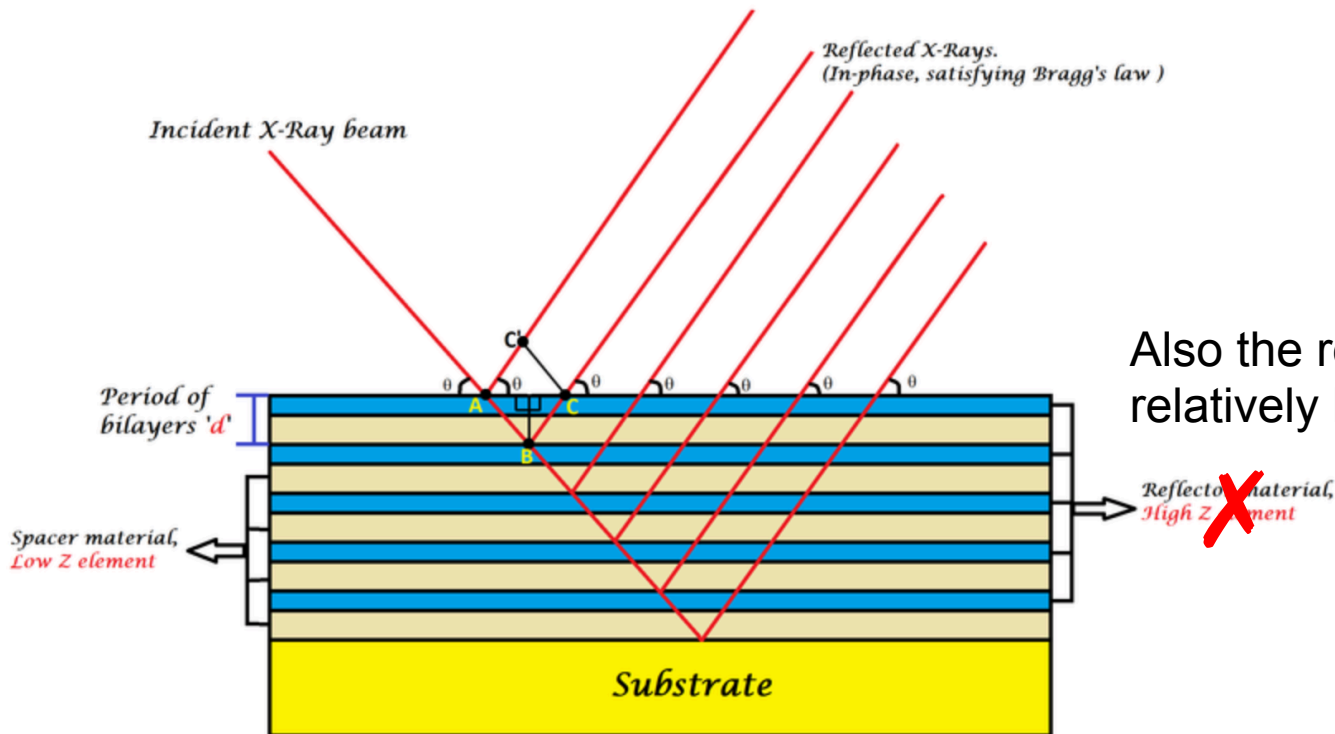
	Horizontal	Vertical
Source-IP (m)	360	360
Demag 2nd set	20	10
q1=	3.540	1.777
Demag 1 <sup>st</sup> set	100	200
p1=	354.045	355.363
p2=	2.3	2.6
q2=	0.115	0.26
Absolute M1 position	354.045	355.363
focus 1 position	357.585	357.14
M2 position	359.885	359.74

Need of short mirrors to go close to the focus; Need of steep angle to collect the entire beam

# Multilayer option to go to 17 mrad @ 8-12 keV

- Use of a reflector (ideally a low Z metal) and a low absorption spacer
- Damage threshold for metal must be low enough
- Each layer reflect a small amount
- Total reflectivity may be large
- Use of a maximum of 60 layers to prevent beam elongation

With 17 mrad incidence, focal distances can be reduced

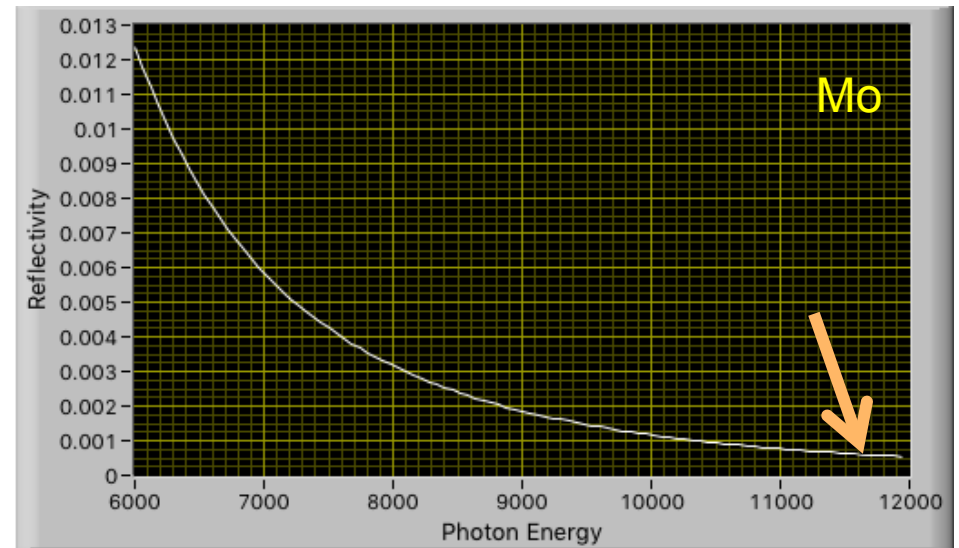
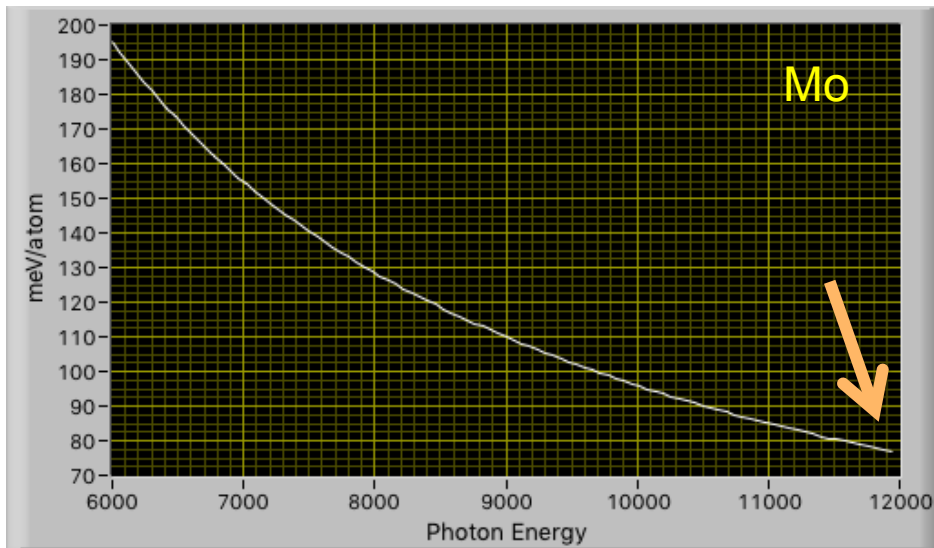
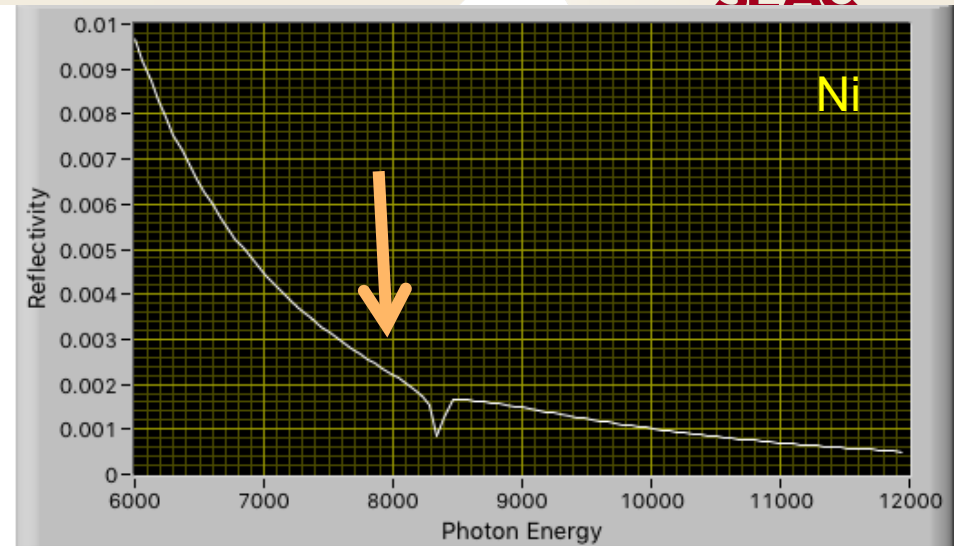
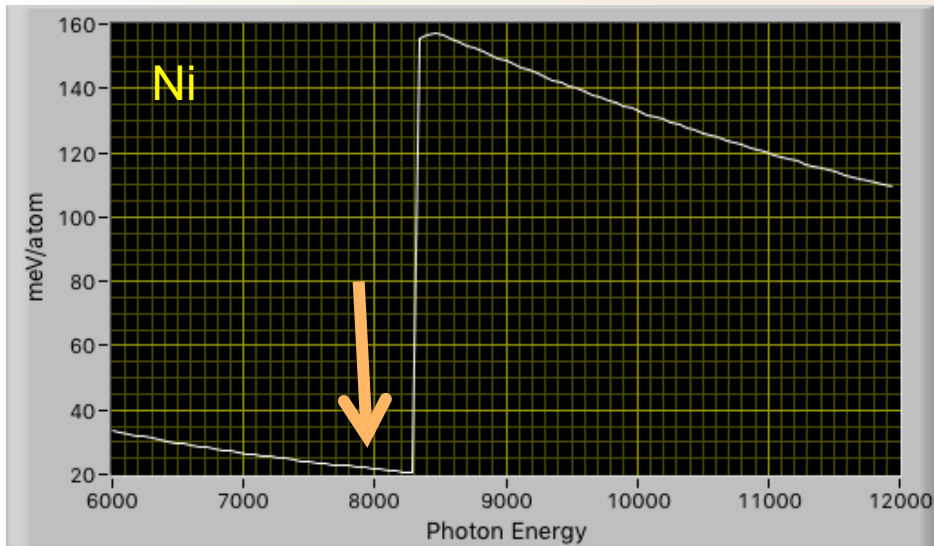


Also the reflector shall be a relatively low Z material

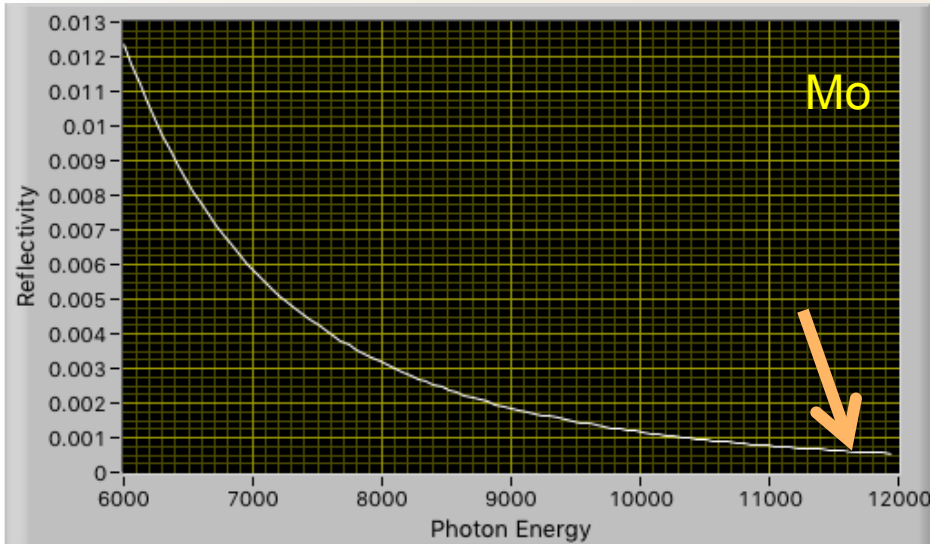


# Possible Multilayer materials @ 17 mrad

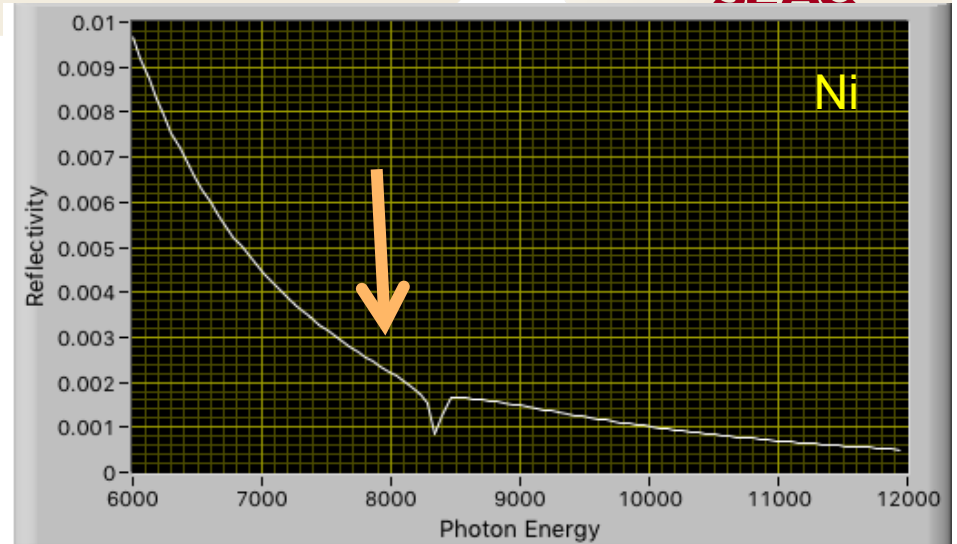
SLAC



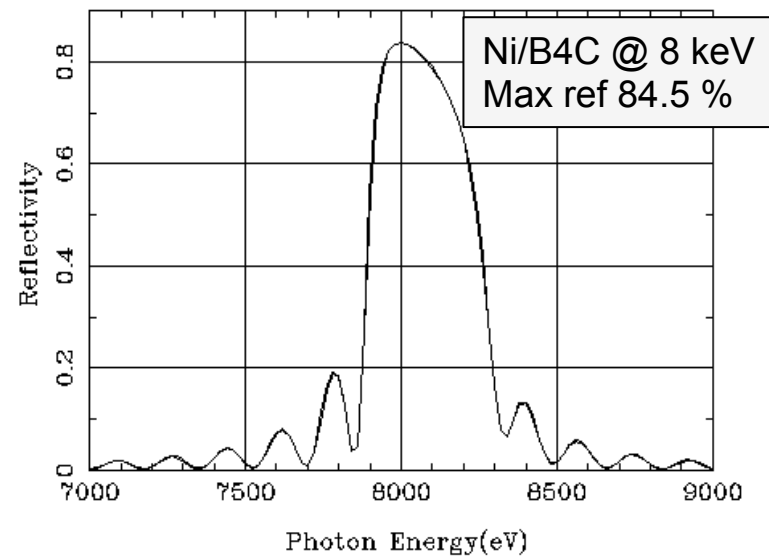
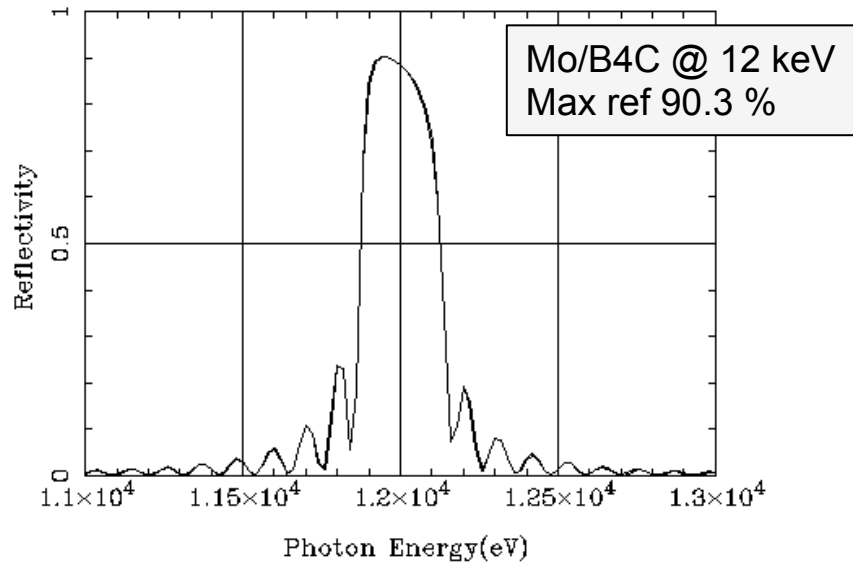
# Possible Multilayer materials @ 17 mrad



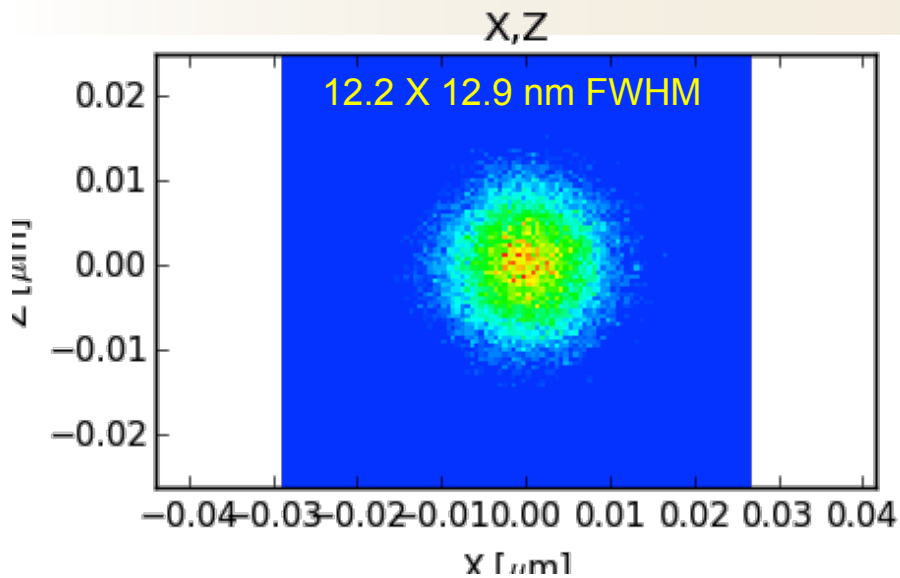
Mo/B4C d=3.03nm s=0.nm N=100 at 1.deg, P=1.



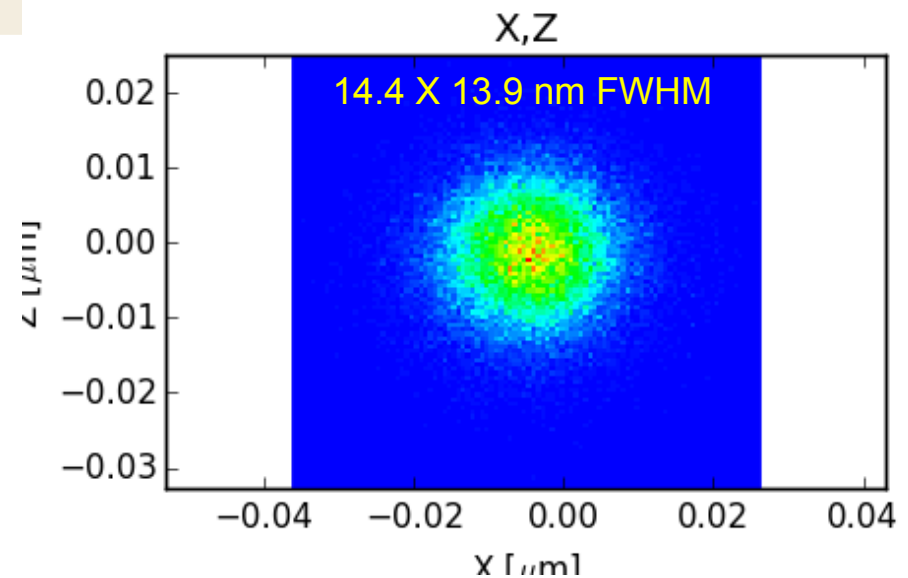
Mo/B4C d=4.62nm s=0.nm N=40 at 1.deg, P=1.



# Spot properties @ 8 keV



Ideal spot / no slope/shape errors



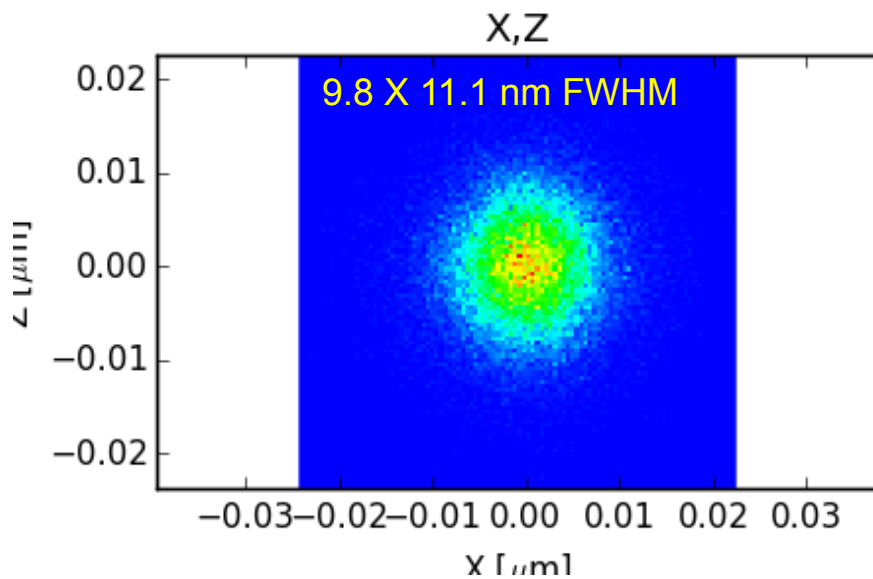
Using 0.3 nm rms on the 800 mm mirror (the best value we have measured so far) and 1 nm rms on the 130 mm mirrors (estimated from polishing and metrology limits)

Peak Power density starting with 1 TW at the source (8 mJ)

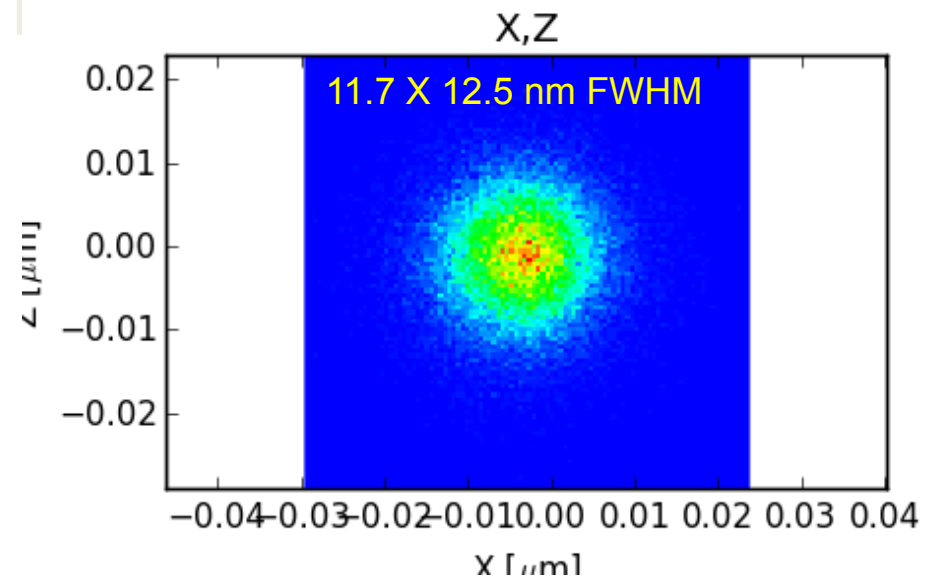
$4.3 \times 10^{23} \text{ W/cm}^2$   
(including reflectivity and elongation)

$3.4 \times 10^{23} \text{ W/cm}^2$   
(including reflectivity and elongation)

# Spot properties @ 12 keV



Ideal spot / no slope/shape errors



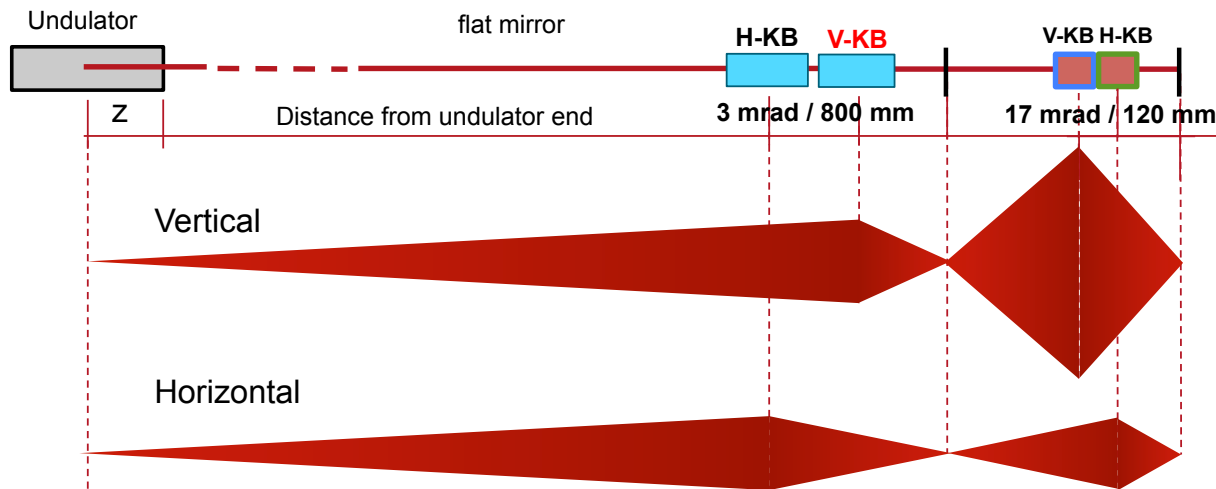
Using 0.3 nm rms on the 800 mm mirror (the best value we have measured so far) and 1 nm rms on the 100 mm mirrors (estimated from polishing and metrology limits)

Peak Power density starting with 1 TW at the source (8 mJ)

$6.4 \times 10^{23} \text{ W/cm}^2$   
(including reflectivity and elongation)

$4.8 \times 10^{23} \text{ W/cm}^2$   
(including reflectivity and elongation)

# Tolerances focus and alignment



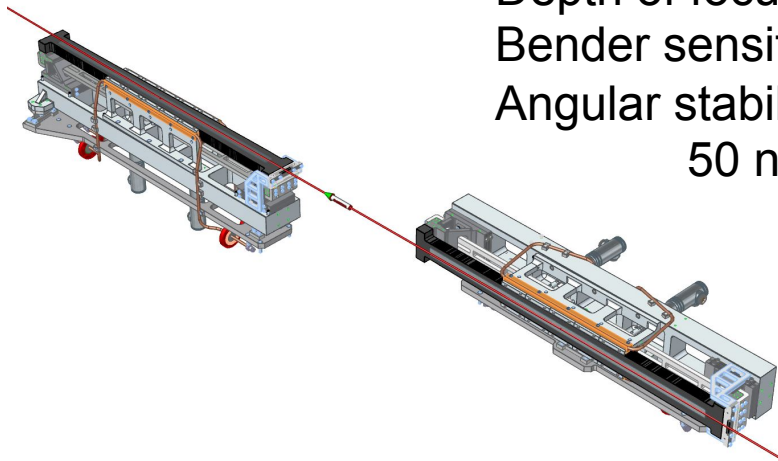
Depth of focus is 1  $\mu\text{m}$ !

Bender sensitivity (mechanical stability of lever arms (0.1  $\mu\text{m}$ ))

Angular stability/alignment:

50 nrad first 2 mirrors

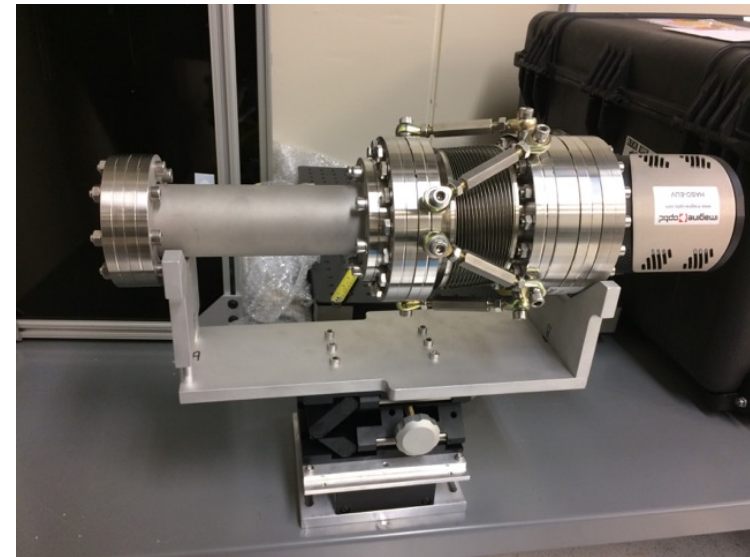
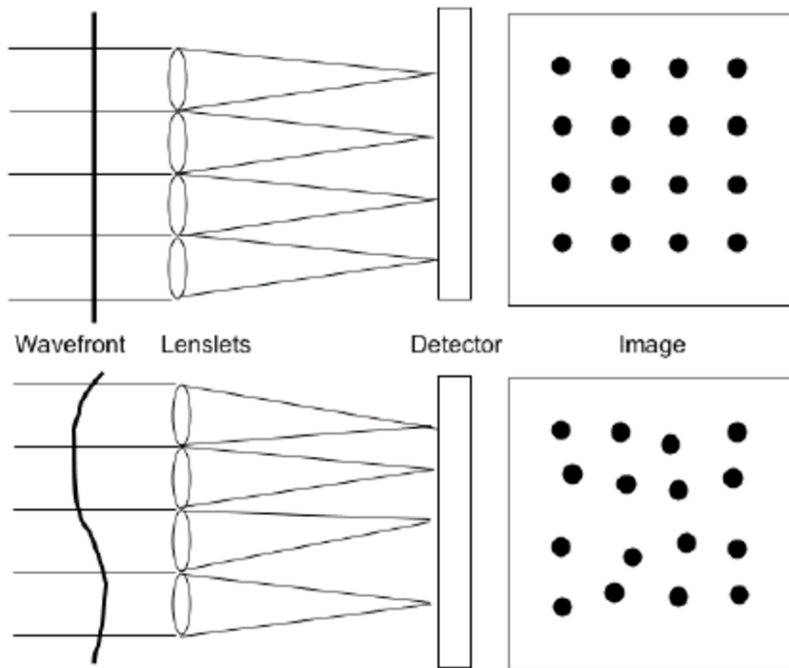
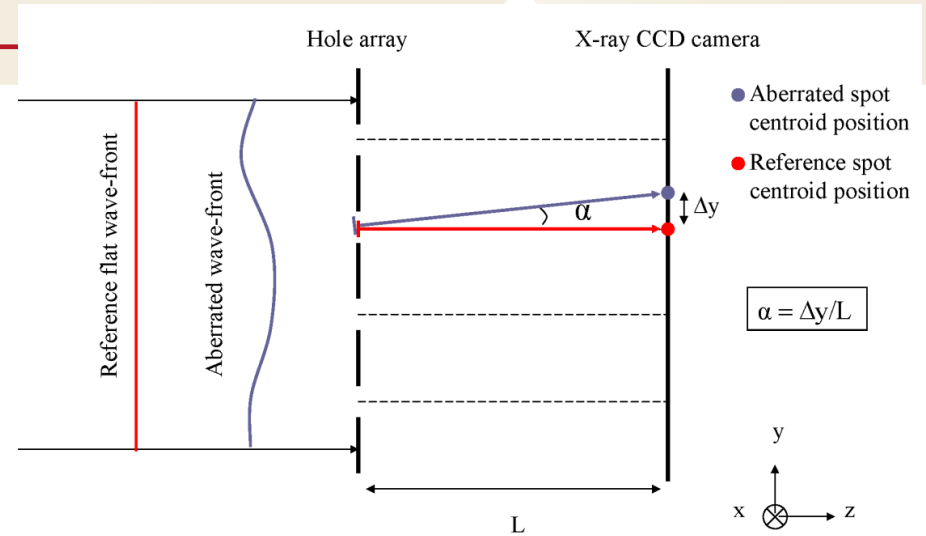
80 nrad second KB set



# Hartman Sensor

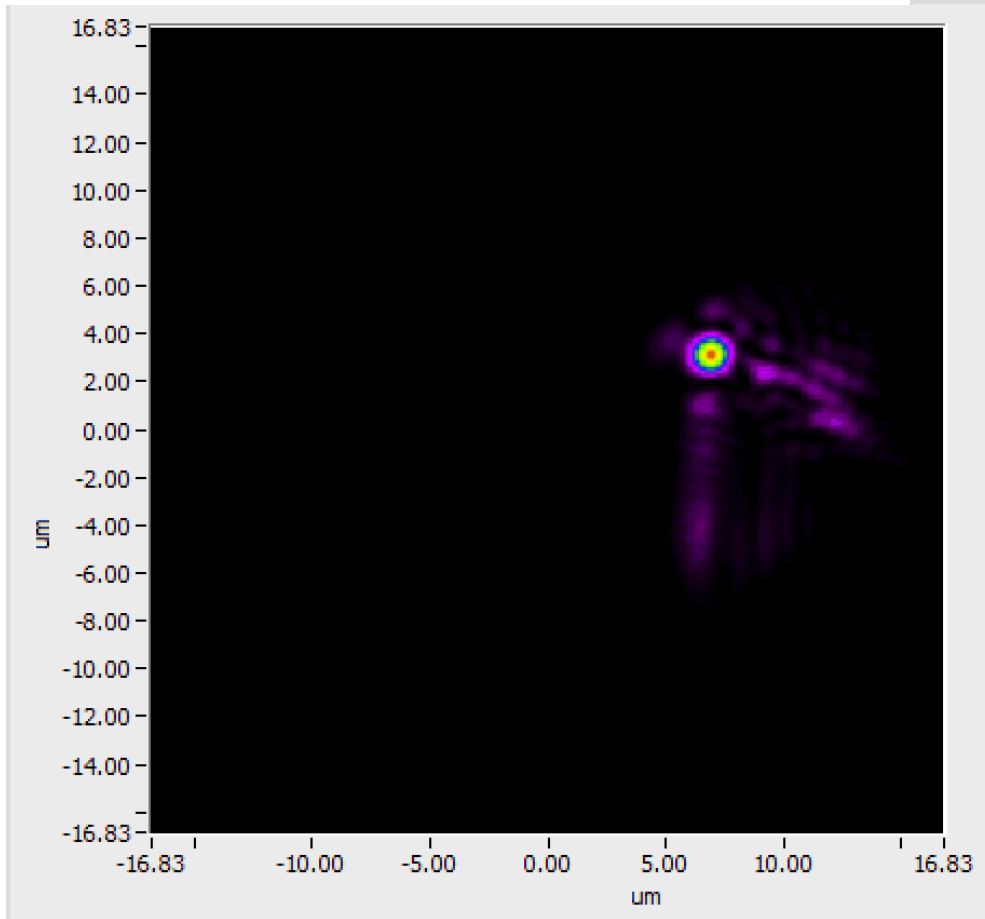
The distorted wavefront hit the various pinholes with different local angles of incidence, producing a non uniform distribution of spots on the detector.

**This can be done on a single shot basis and at very low power (using filters). Power can then be “restored”.**

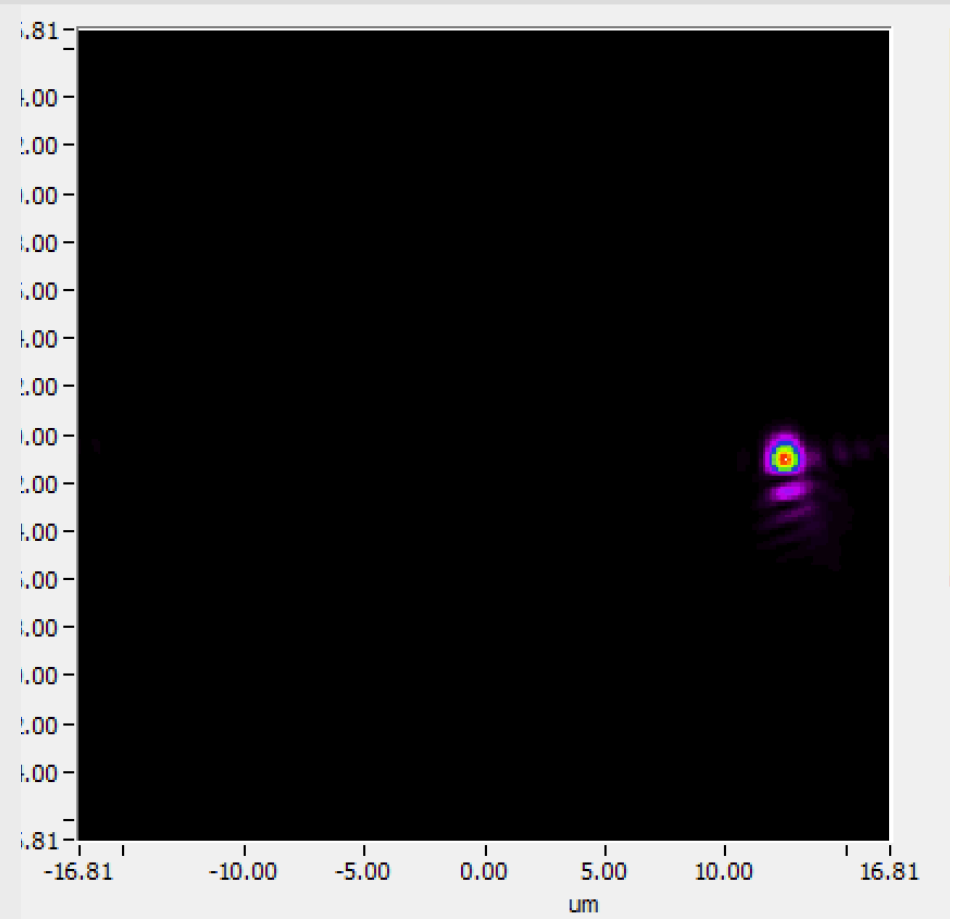


# Reconstructed image around the focus position

Before WFS assisted KB optimization



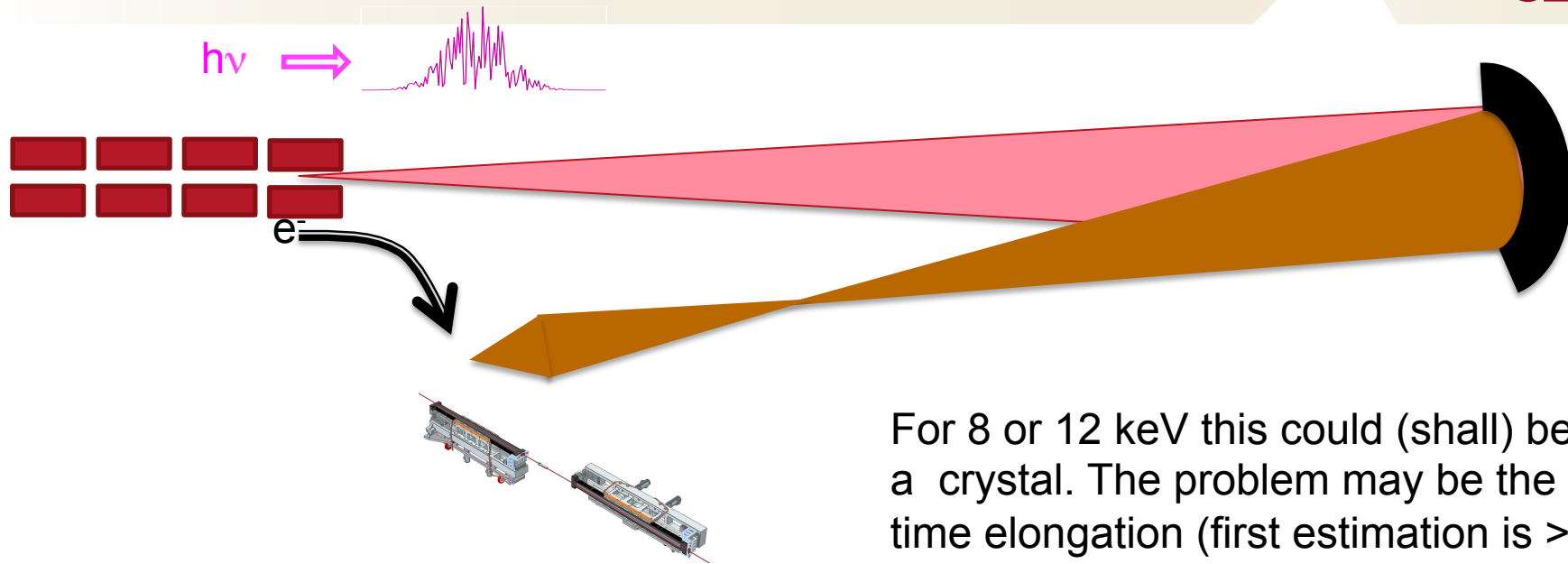
After WFS assisted KB optimization





# Reaching the Schwinger field

presented by Claudio on Wednesday



For 8 or 12 keV this could (shall) be a crystal. The problem may be the time elongation (first estimation is  $> 30$  fs)

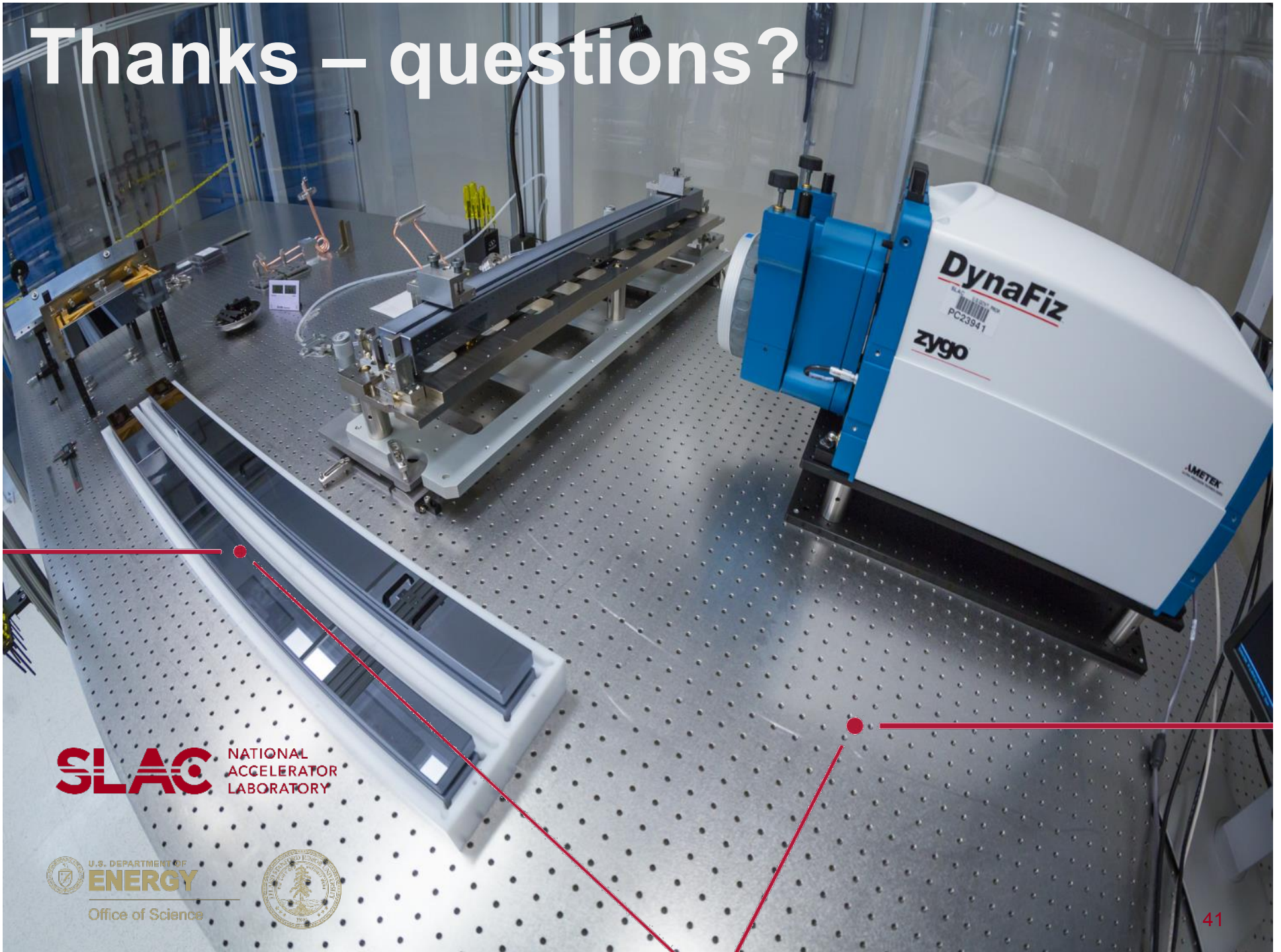
Or, at, for instance 13 nm (95 eV), one can use proven multilayer (Mo/Si, 6.7 nm d-spacing, 40 layers)

# Conclusions

This talk was an “FYI”... optics can do a lot of damage  
... but there are not only bad news..  
TW is not out of reach... just need some more effort

- High average power source (not necessarily the main topic of this workshop) have seen R&D to face problems like:
  - Mitigation of the effect of thermal deformation
  - Mitigation/removal of the carbon contamination from optics
  - Wavefront sensing to optimize the spot (with full power *Work in Progress*)
  - Introducing the cooling scheme on adaptive optics (not discussed)
  - .....
- High peak power (pulse energy) have seen some R&D so far (after the initial boosts), mainly on damage studies. Some of the High Heat load R&D efforts are important for High Peak Power sources too. Having a beamline reaching  $10^{24}$  w/cm<sup>2</sup> is not impossible!
- Left to do:
  - Having a broad(er) scientific community requiring access to TW to boost the R&D
  - Improve the beam and optic stability
  - Crystals and Multilayer in either forward or back diffraction geometry to preserve the pulse length (and survive the beam)
  - High power diagnostic (with close loop feedback with the optics)
  - .....

# Thanks – questions?



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